



Choosing the Best EPIC-SEM for Your Experiment

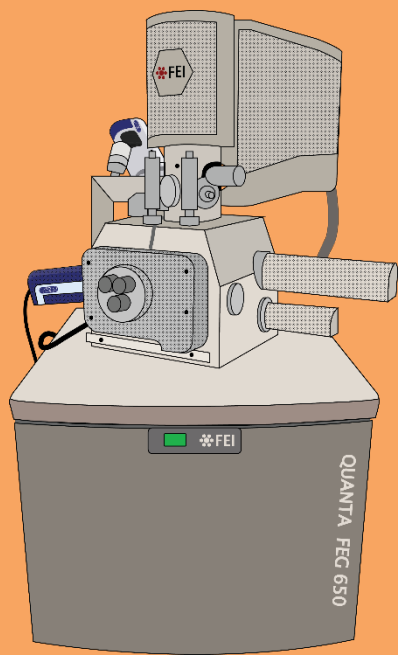
Tirzah Abbott – EPIC-SEM Facility Manager

Nick Gogola – Asst. Core Scientist

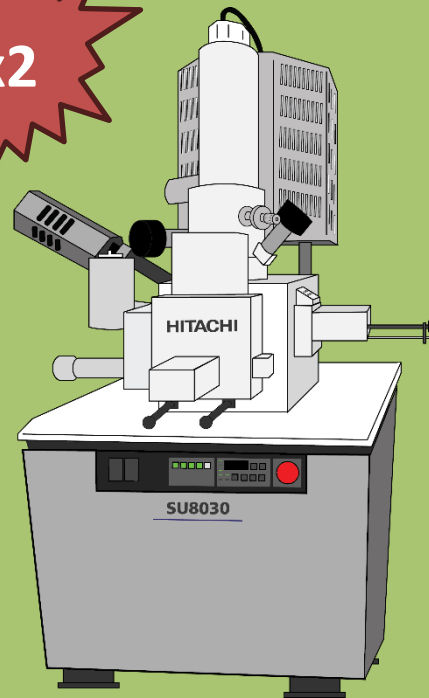
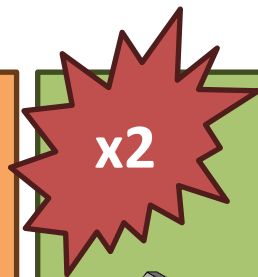
2023



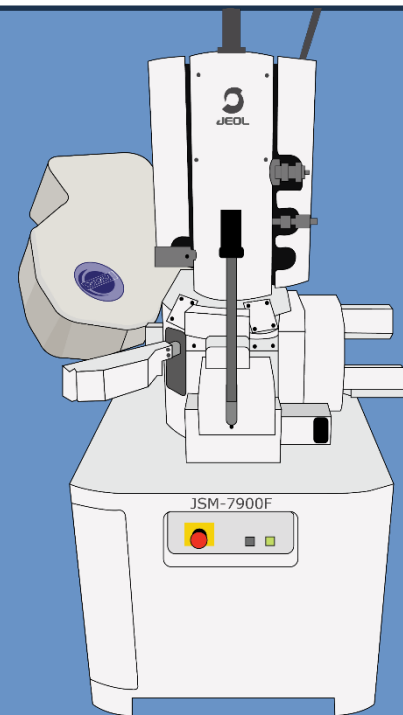
Hitachi
S-3400N



Quanta
650 FEG



Hitachi S-4800
and SU8030



JEOL JSM-
7900F

Overview

Background

What is SEM and how does it work

Electron Detectors

Image generation with different signals electron-specimen interaction

SEM Modes and Techniques

Advanced imaging and microanalysis techniques

SEM's at NUANCE

The different SEM's with strengths and weaknesses

Background



Figure from MyScope.com

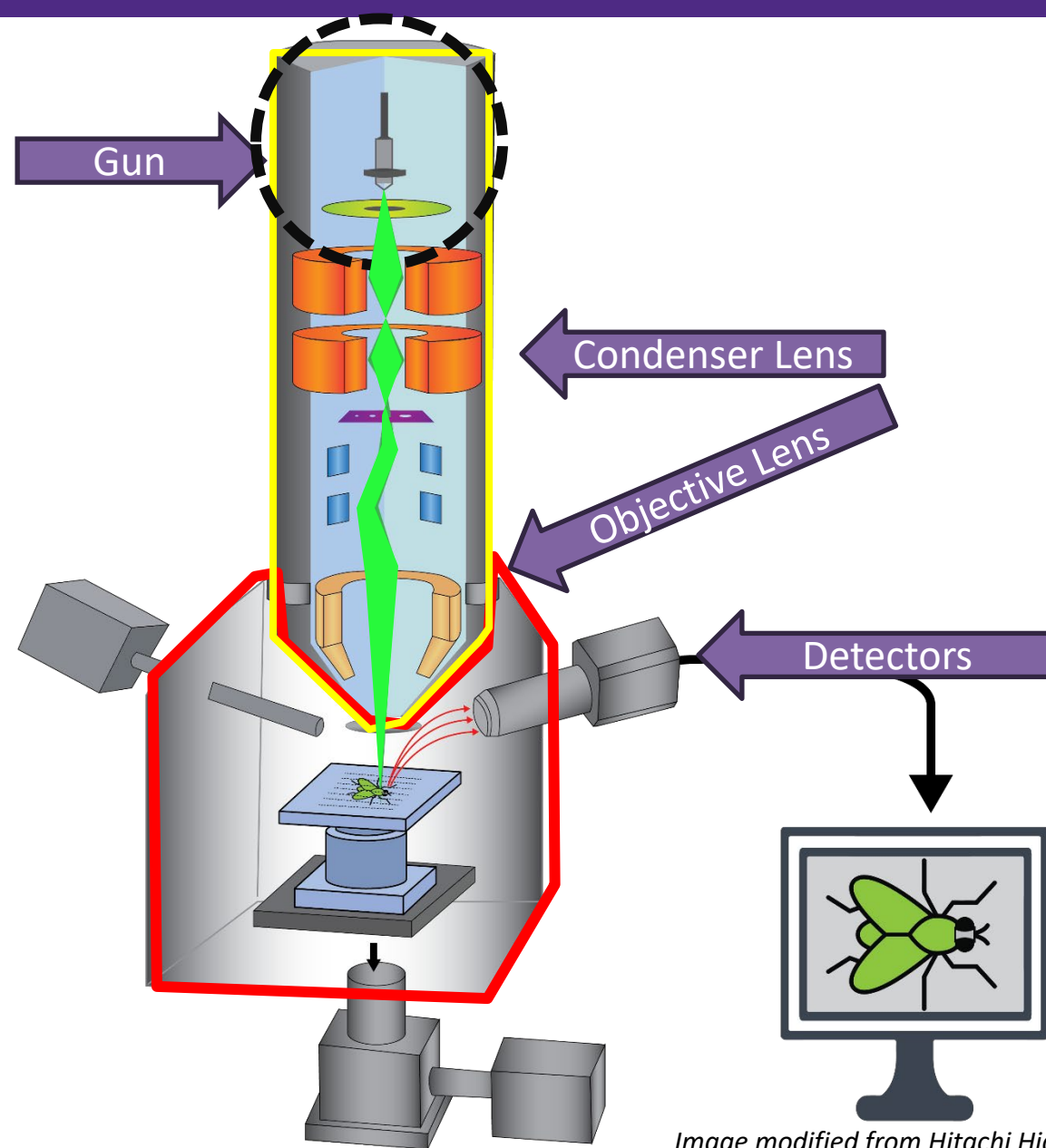
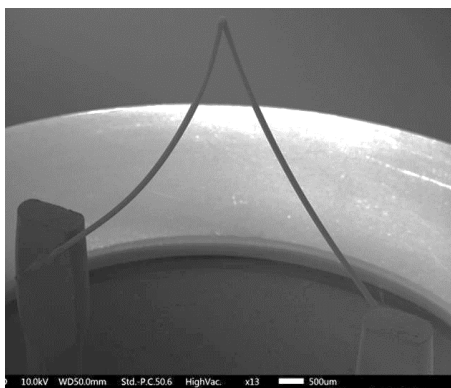
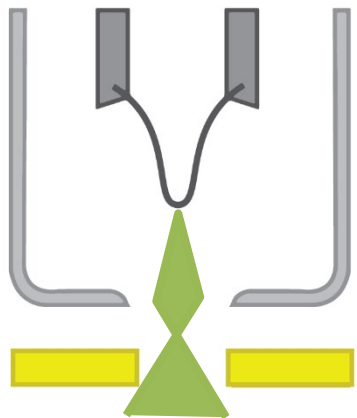


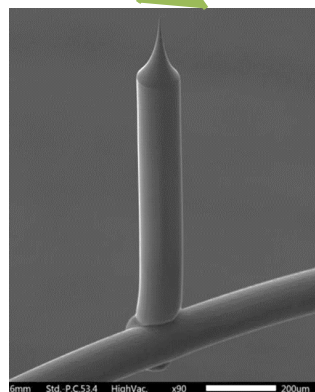
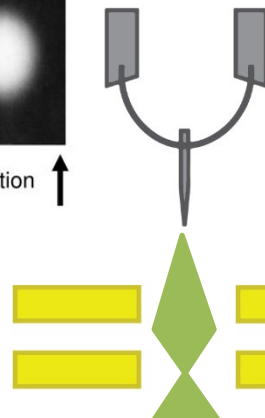
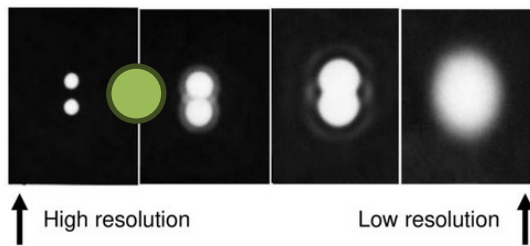
Image modified from Hitachi High-Tech

Tungsten Filament



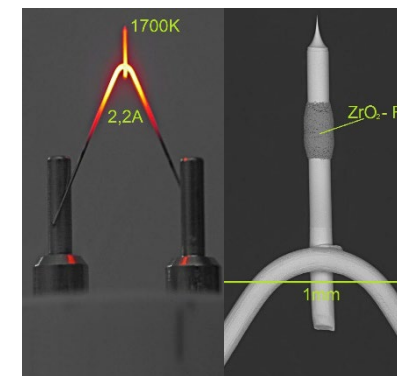
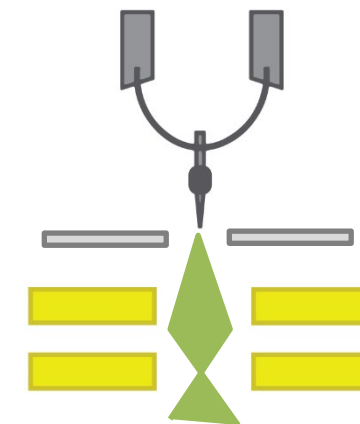
Source Diameter	Resolution	Brightness	Energy Spread	Stability
↑	↓	↑	↑	↑

Cold Field Emitter



Source Diameter	Resolution	Brightness	Energy Spread	Stability
↓	↑	↑	↓	↓

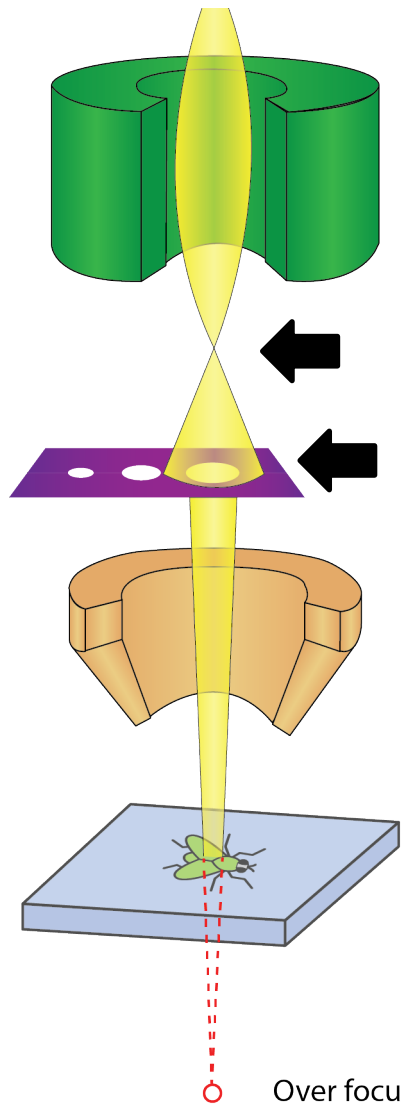
Schottky Emitter



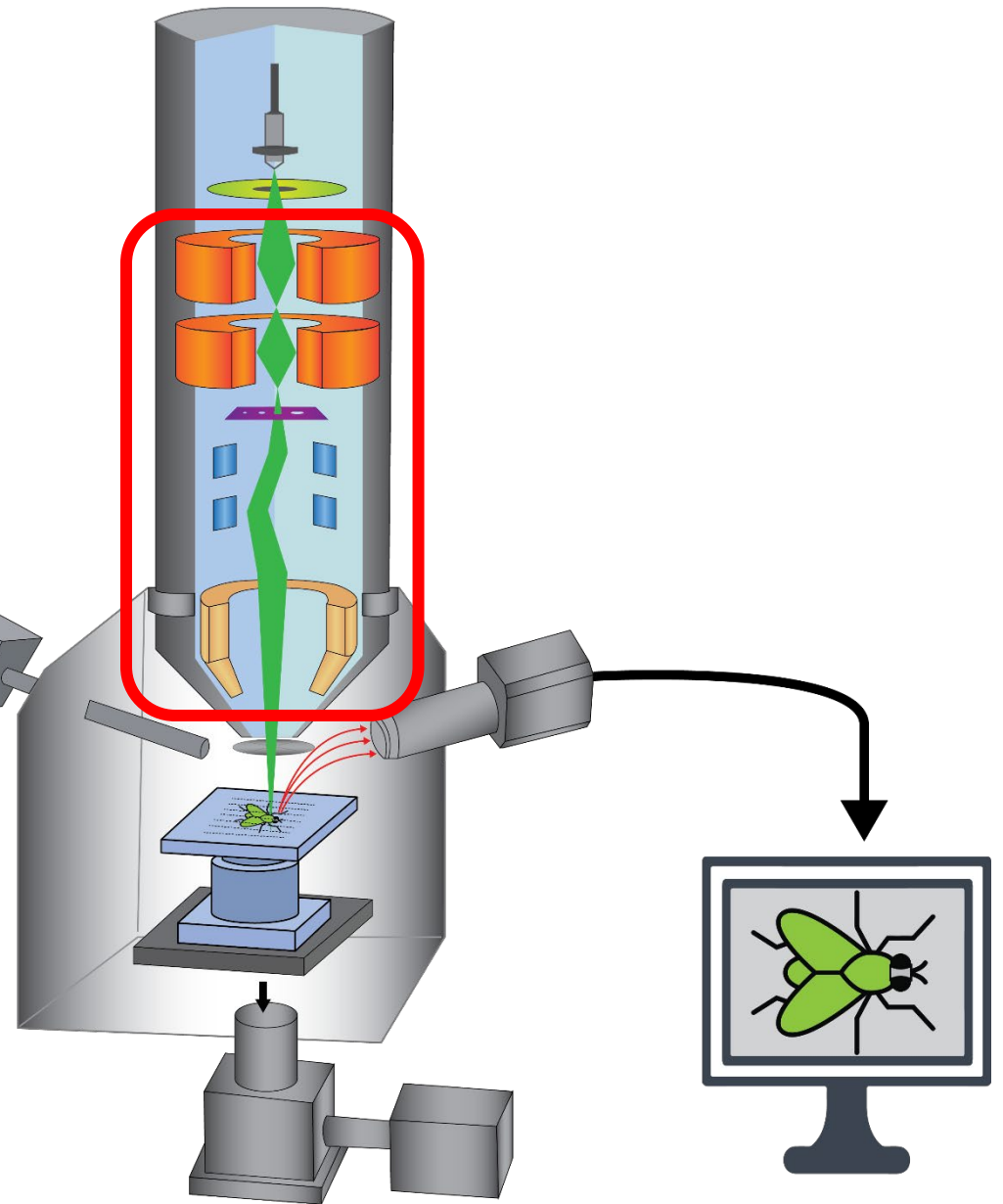
Source Diameter	Resolution	Brightness	Energy Spread	Stability
↓	↑	↑	↓	↑

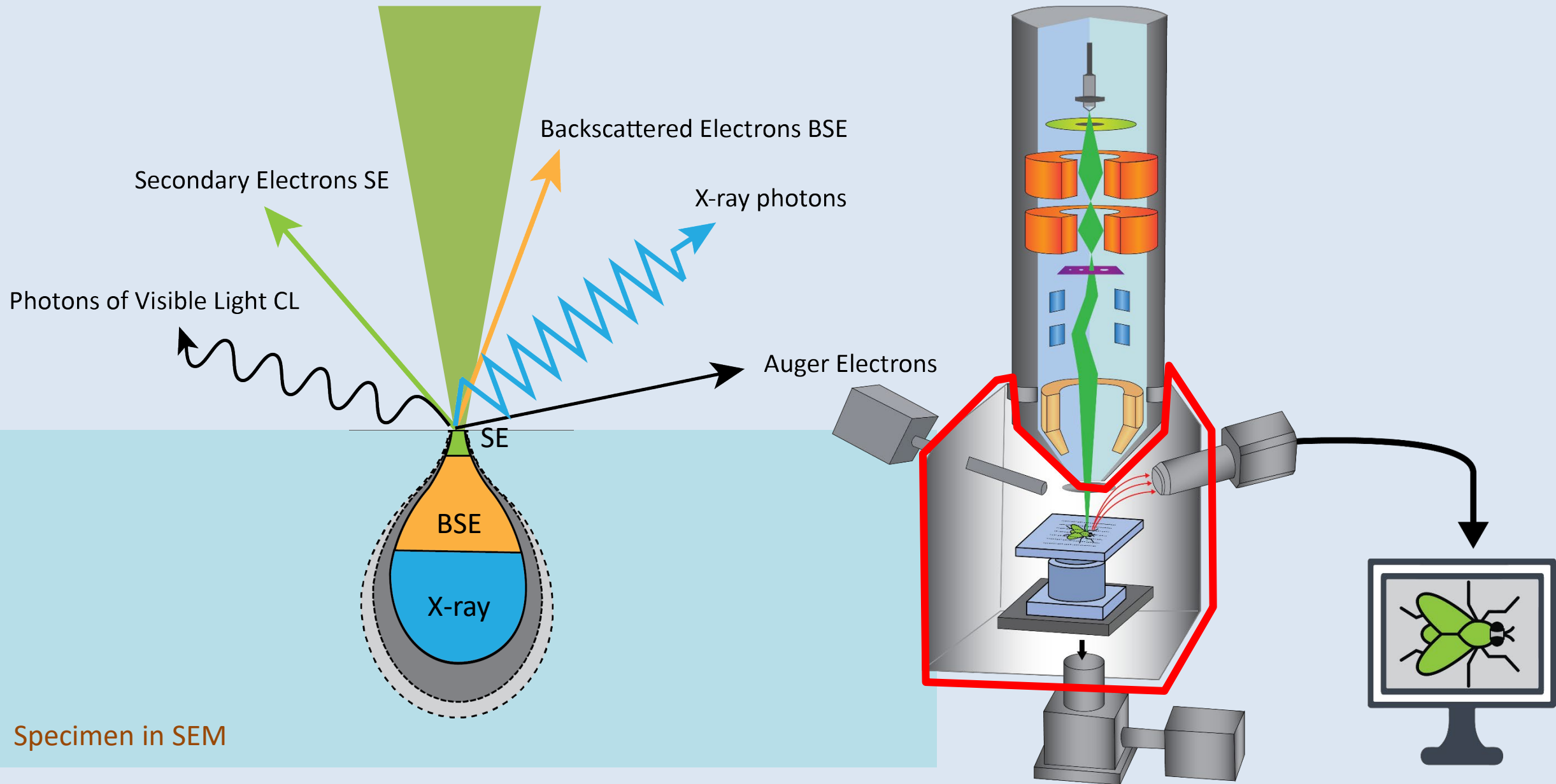
Images from Anwar 2018

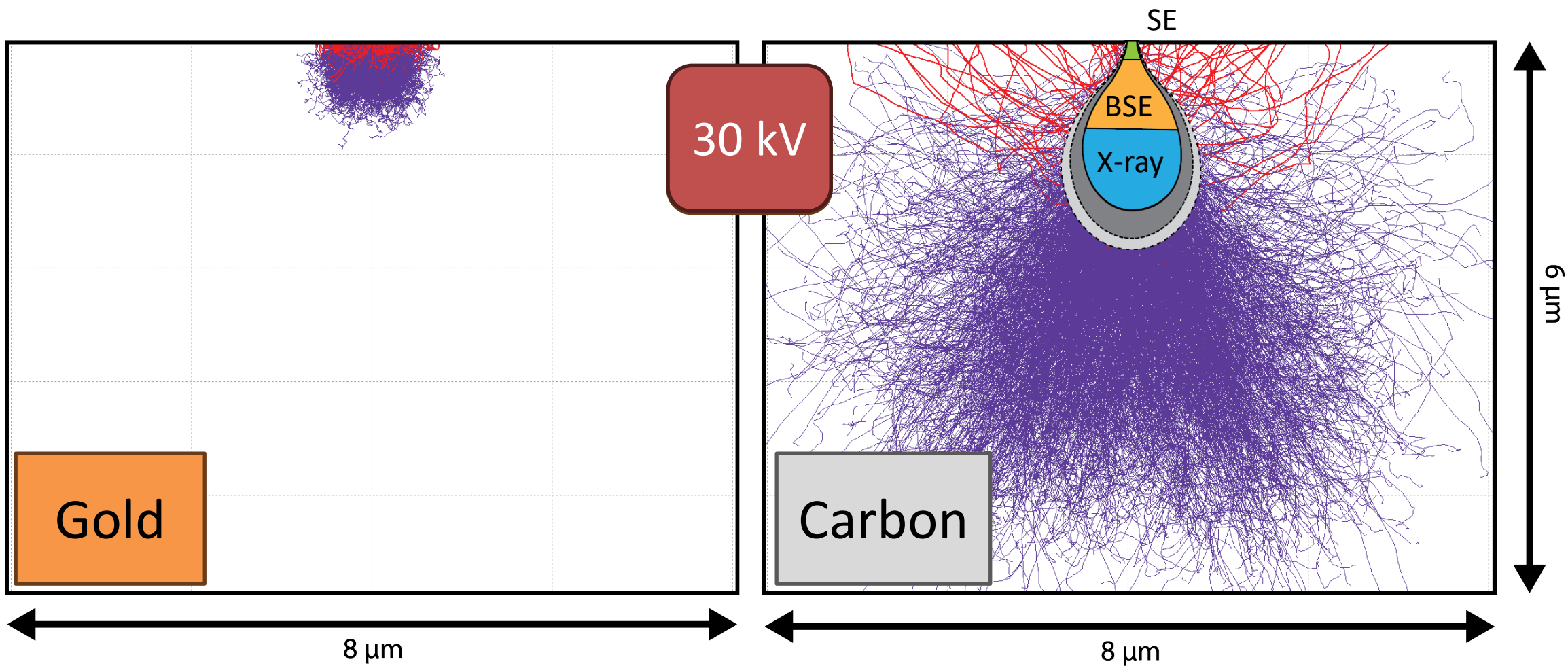
Condenser Lens



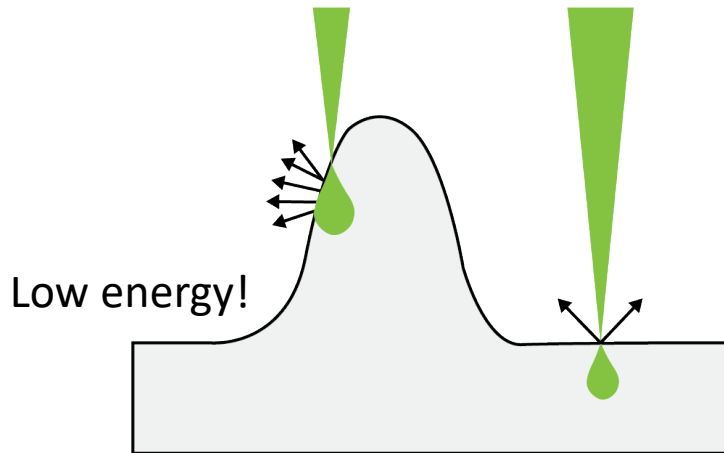
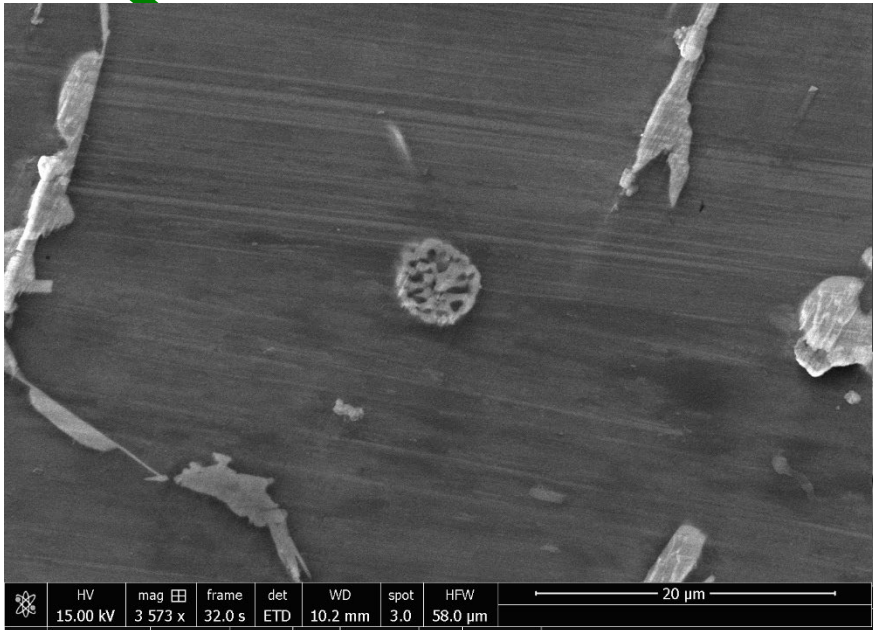
Objective Lens



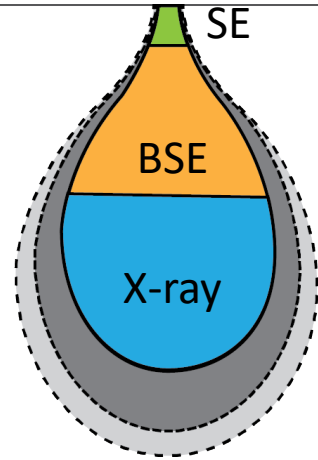
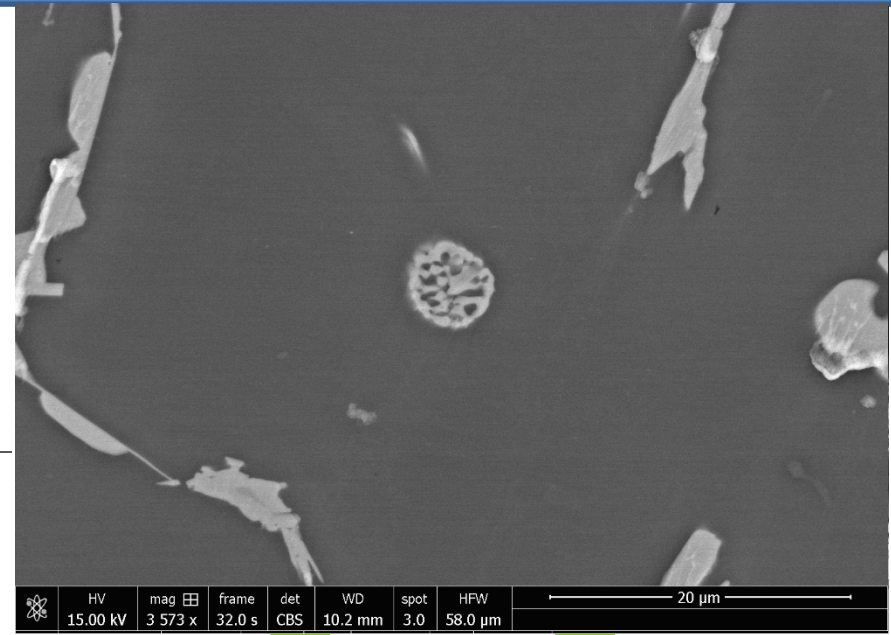




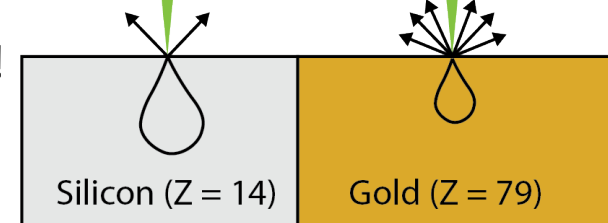
Secondary Electrons



Backscatter Electrons

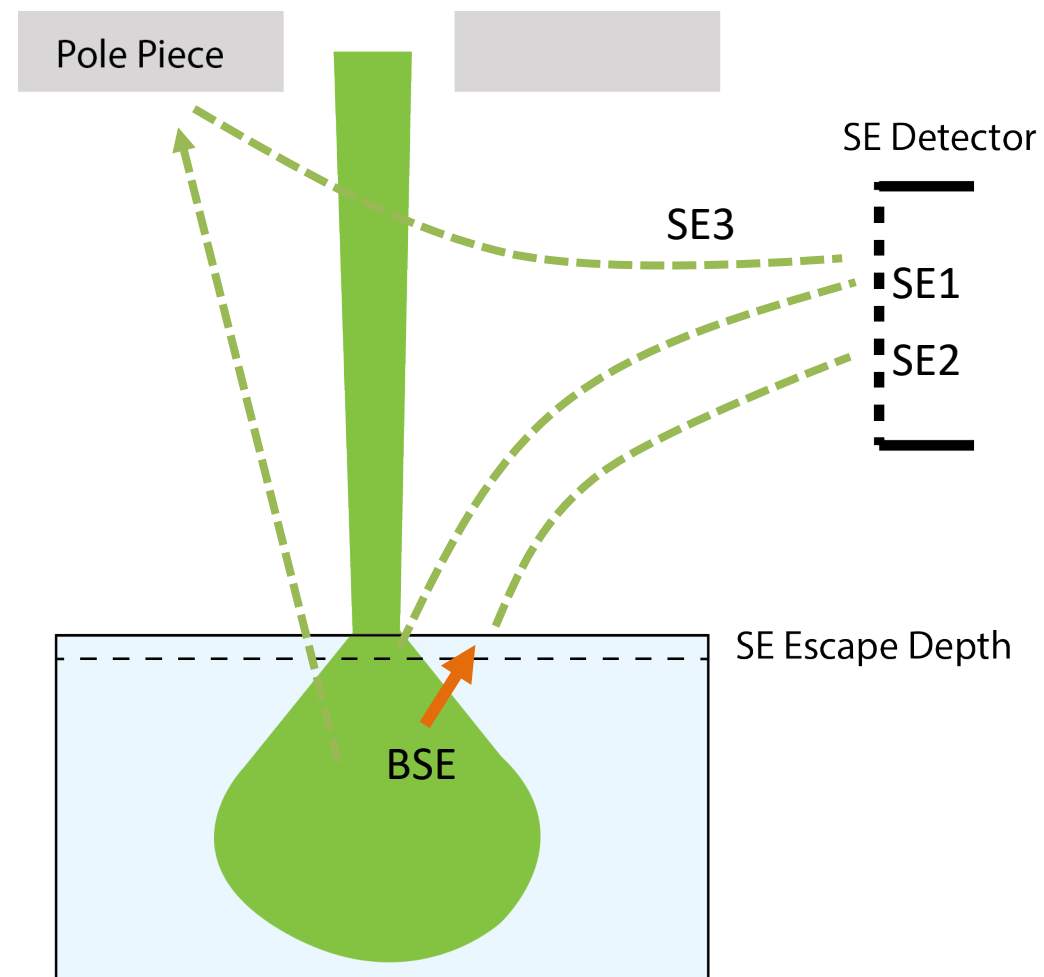


High energy!

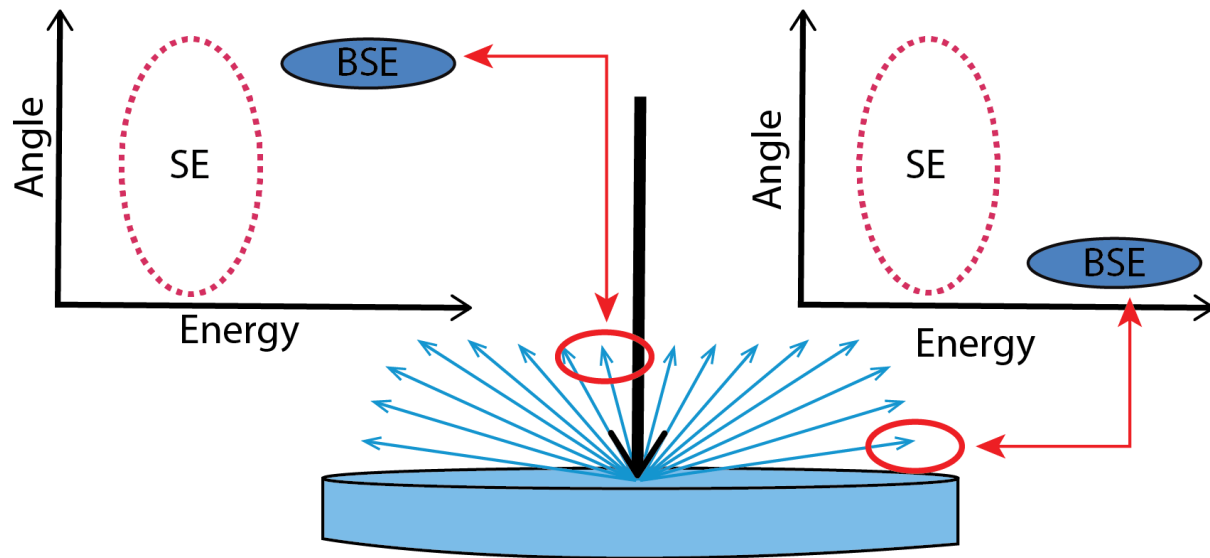


Secondary Electrons

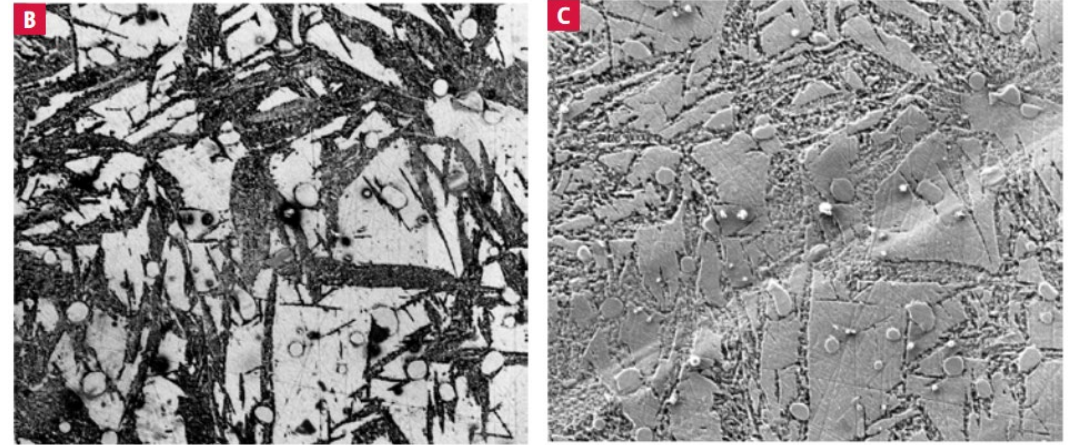
SE1	Incident probe	Most surface sensitive, high res
SE2	BSE Leaving the sample generating SE	Low res, some compo information
SE3	BSE hitting walls of chamber	Noise



Backscatter Electrons



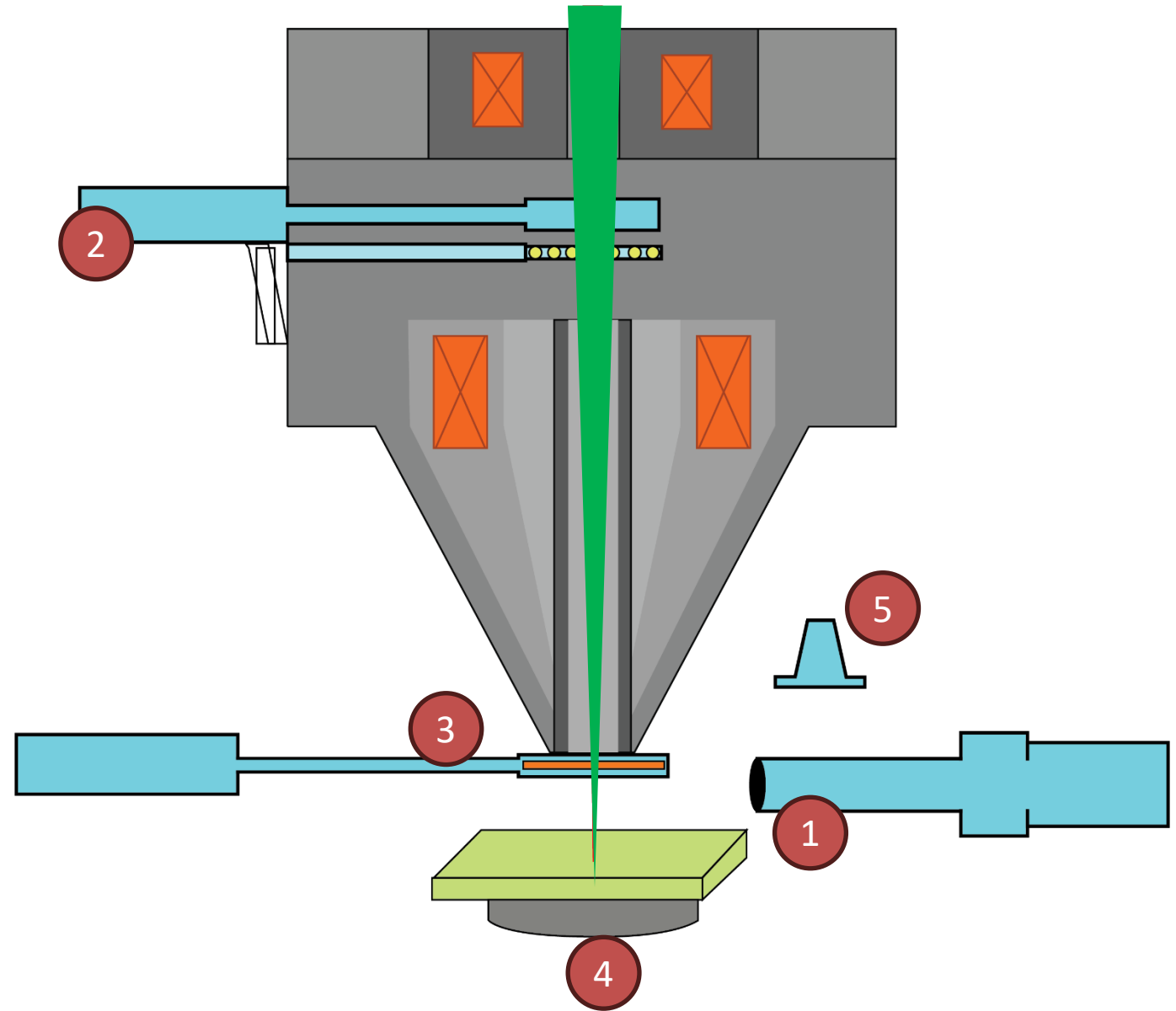
- Angles of elastic scattering range from 0-180 degrees



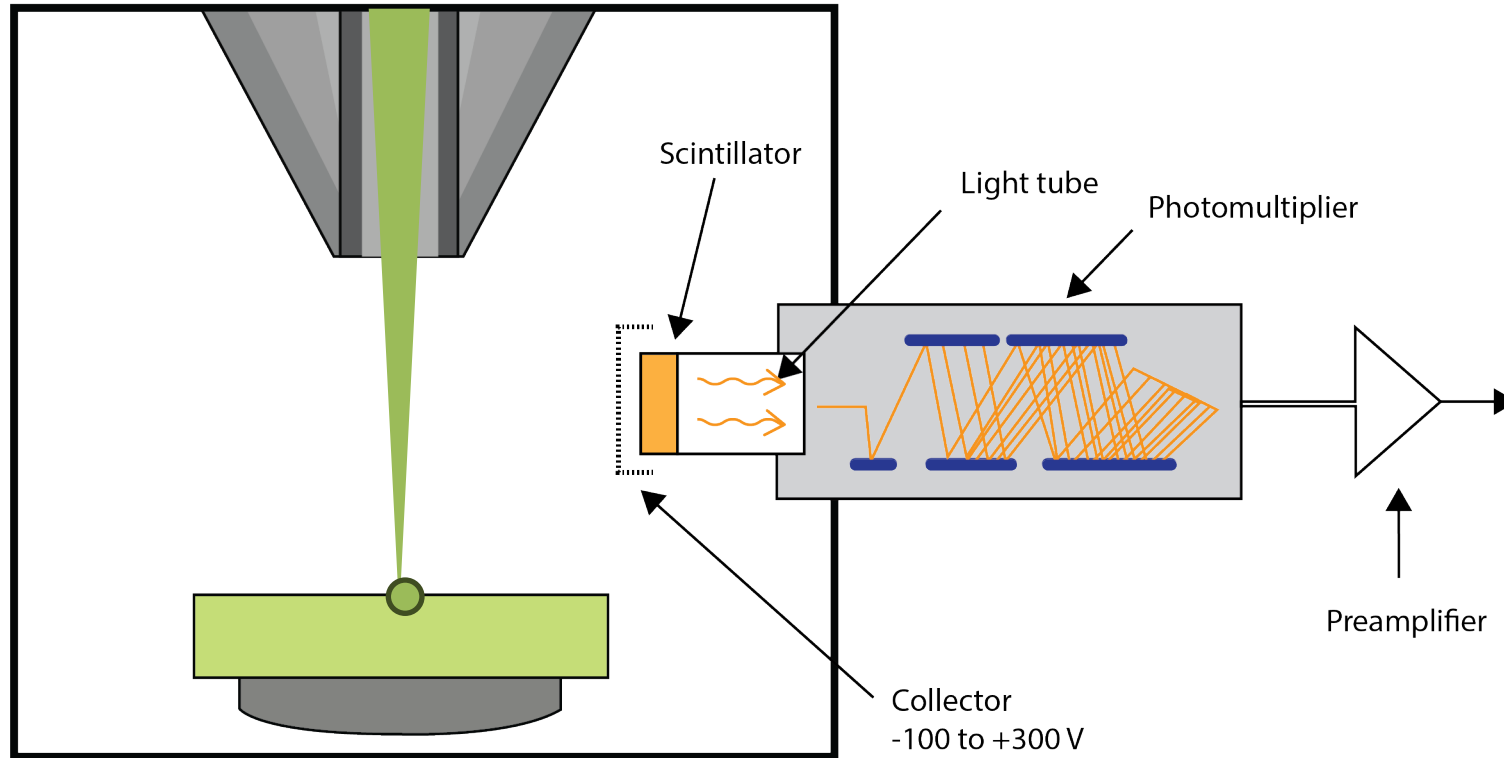
Steel sample (B) high angle BSE showing z contrast and (C) low angle BSE showing topography (photos from FEI)

Electron Detectors

1. Lower SE Detector (EHT detector)
2. In-Lens (upper) SE Detector
3. Backscatter Electron Detector
4. STEM Detector
5. Others (Low Vac, etc.)



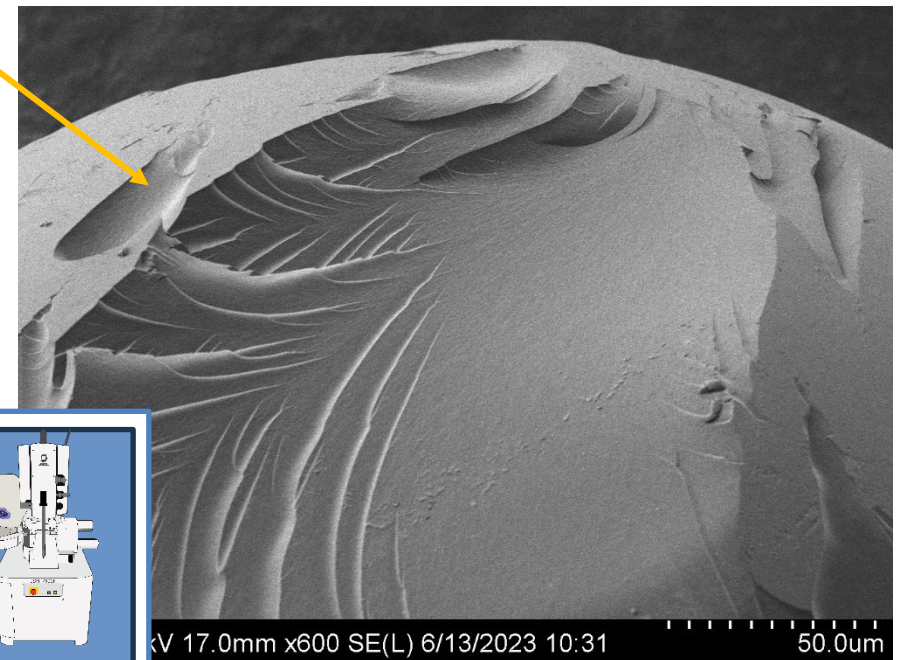
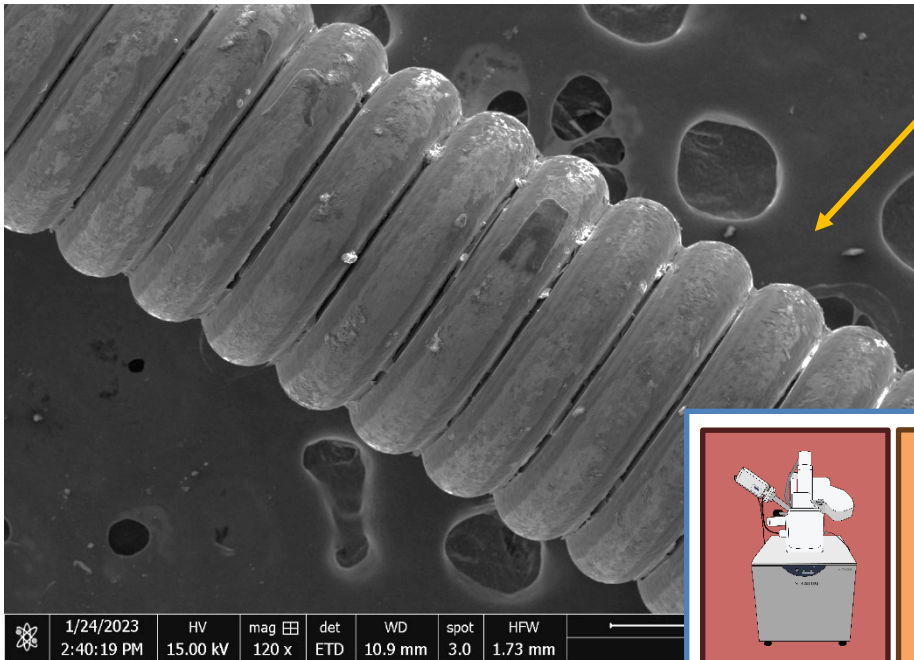
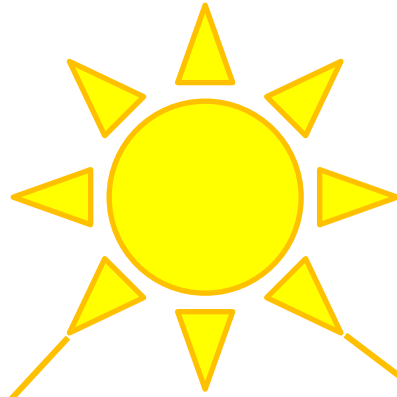
1. Lower Secondary Electron Detector



- Directional illumination due to detector geometry
- Rapid characterization of surface topography
- Decreased signal at short WD (< ~10 mm)
- Reduced charging effects

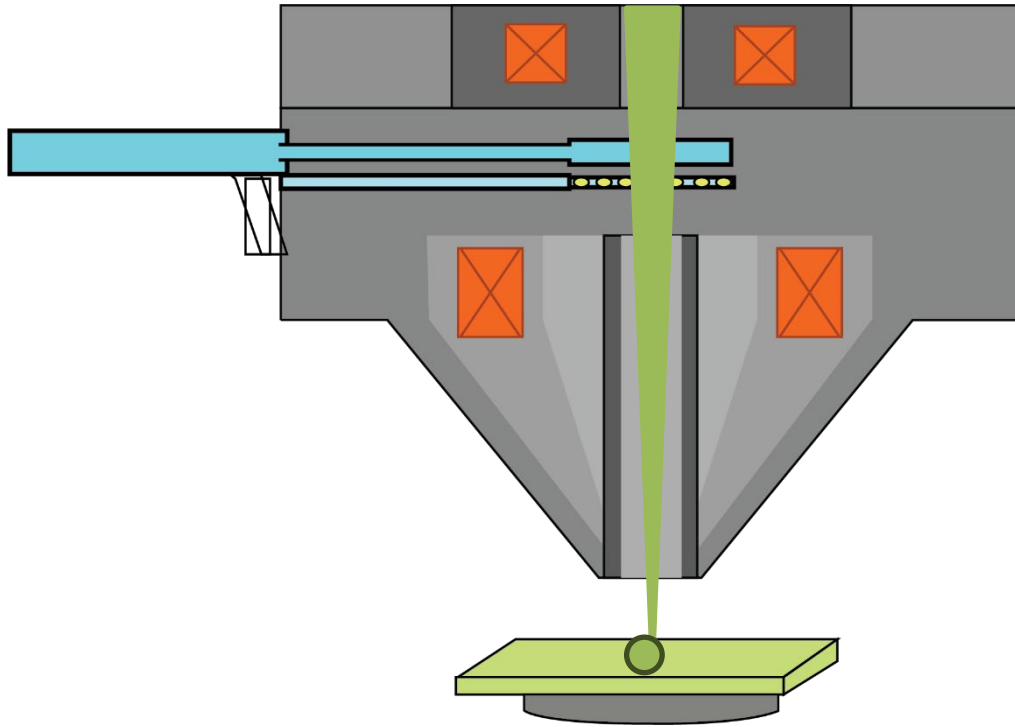
Lower detector: ~ 40% SE3, 45% SE2, about 15% SE1 (and some direct BSE signal)

SE Detector Examples



 Hitachi S-3400N	 Quanta 650 FEG	 Hitachi S-4800 and SU8030	 JEOL JSM- 7900F
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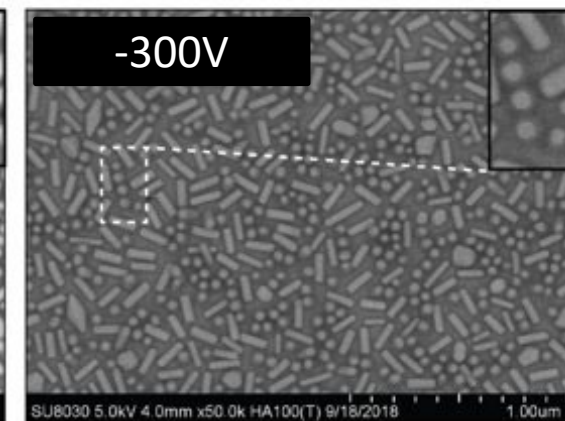
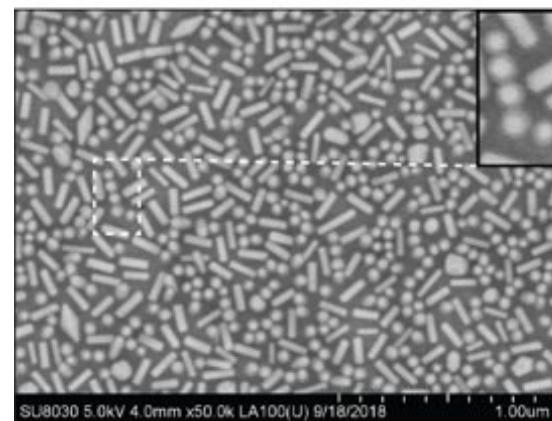
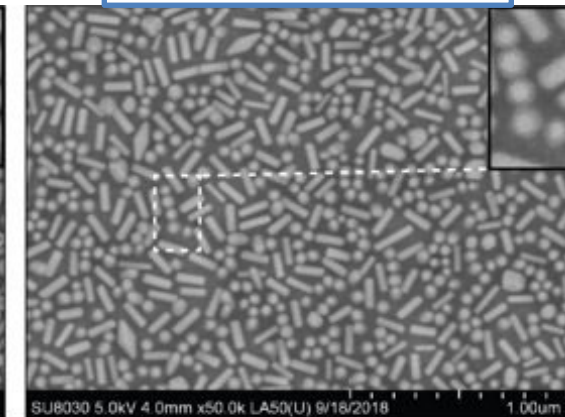
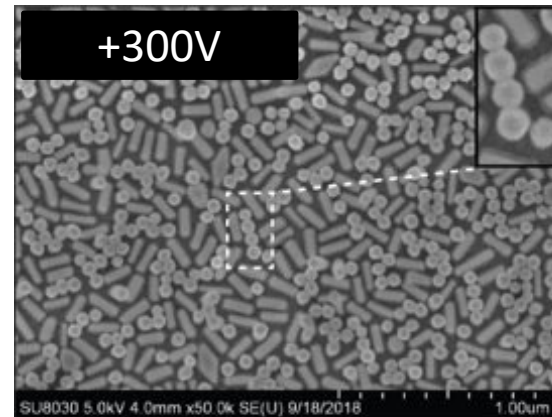
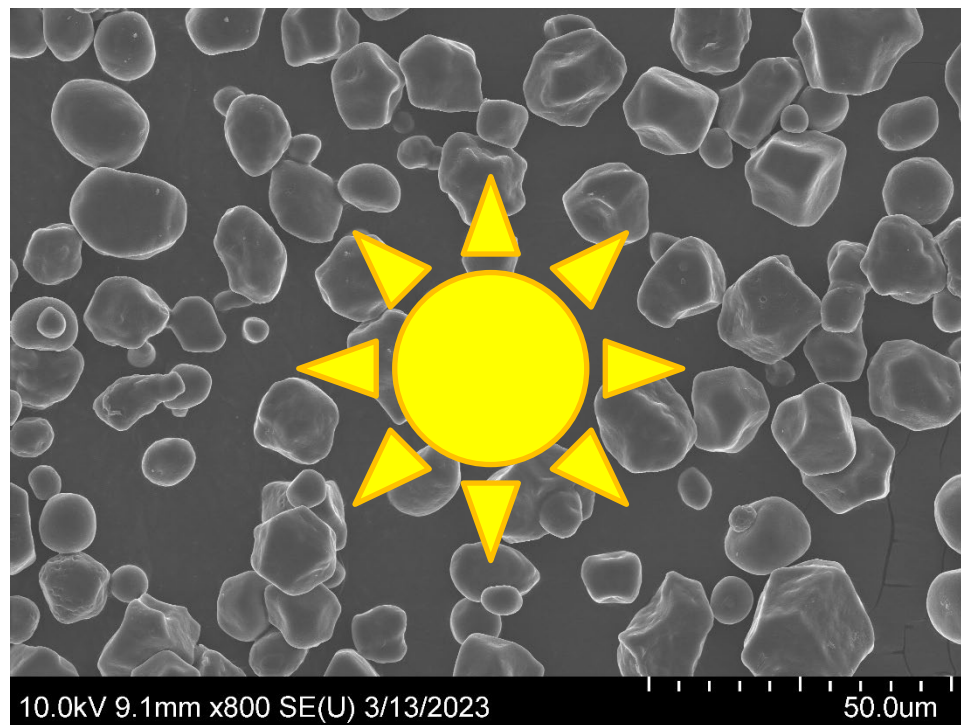
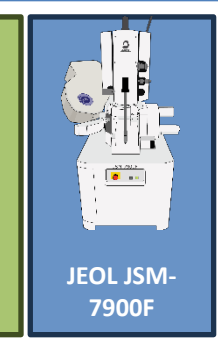
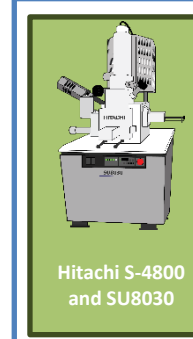
2. In-Lens (upper) Secondary Electron Detector



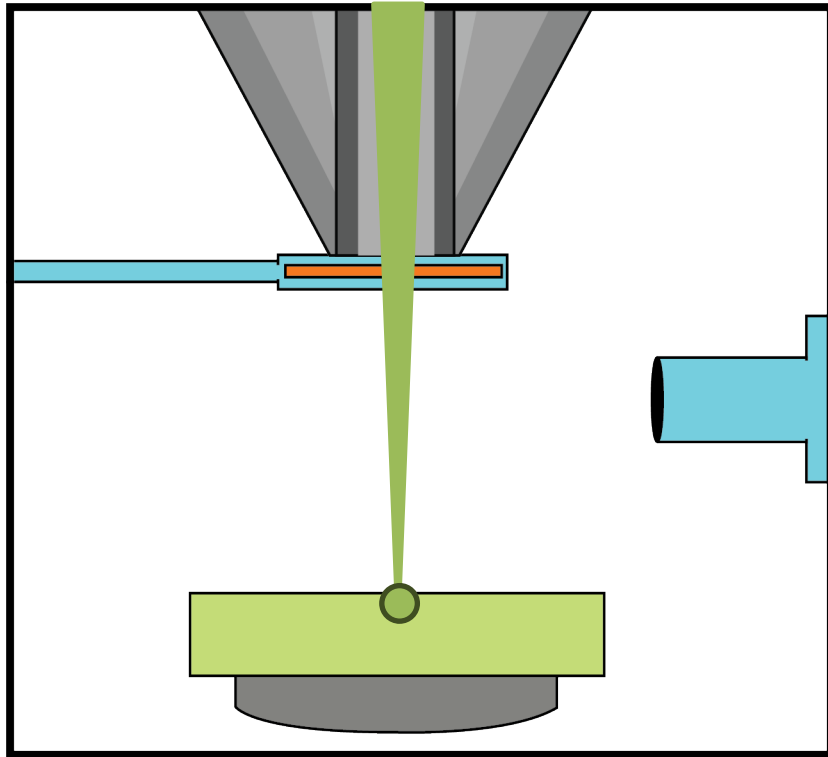
- Signal Varying Mechanism - detect both SE and BSE
- Higher resolution imaging
- Optimum performance at shorter WD (< ~10 mm)
- More uniform illumination than lower SE Detector

Upper detector: ~75% SE2 and 25% SE1.

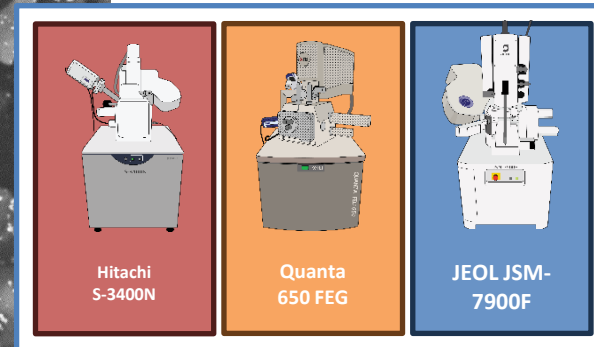
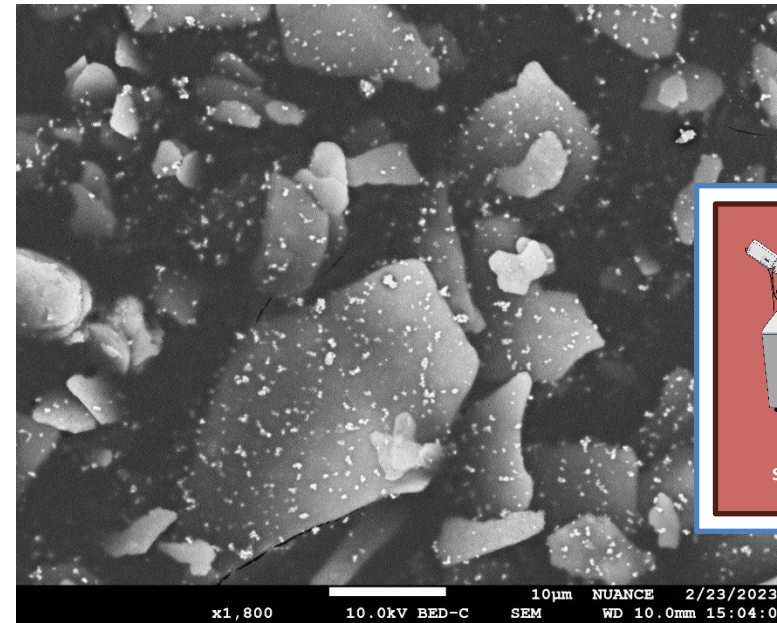
Examples – upper SE



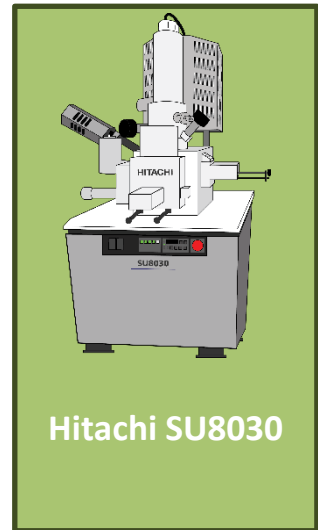
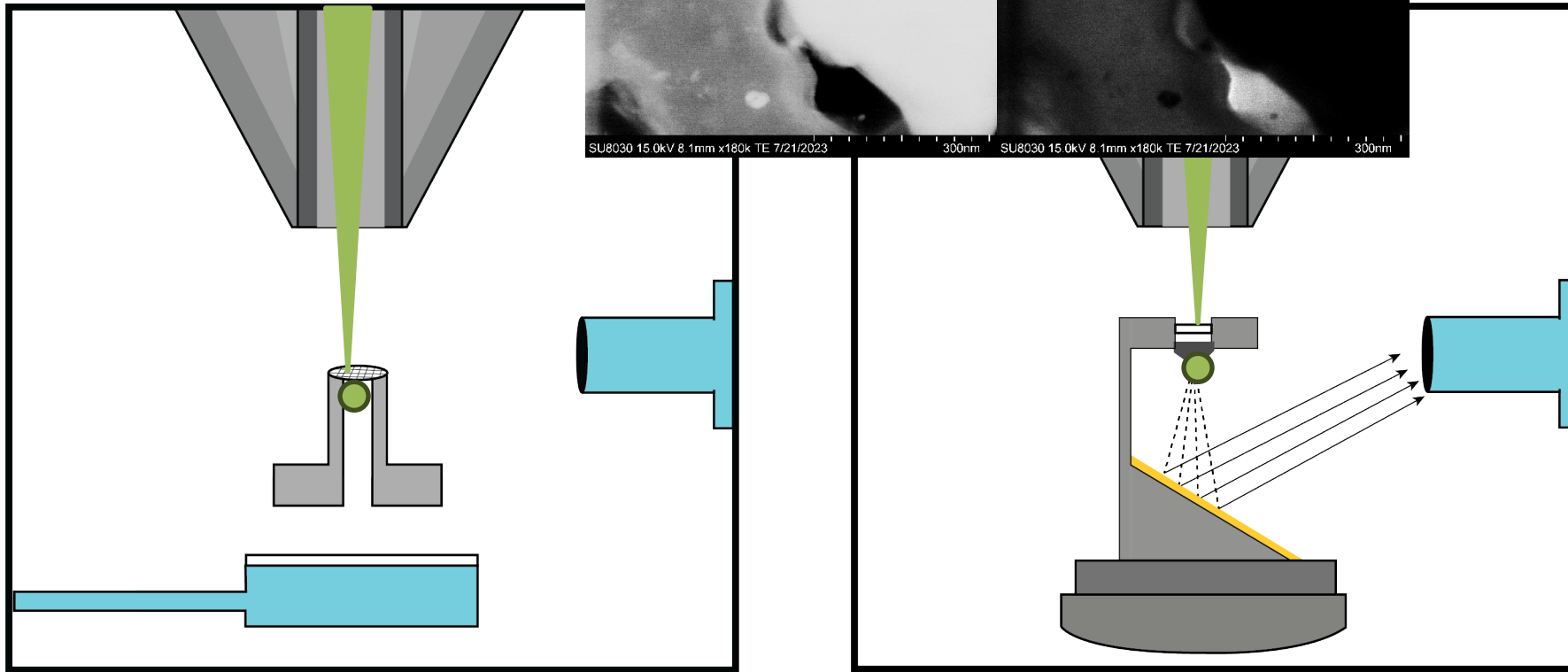
3. Backscatter Electron Detector



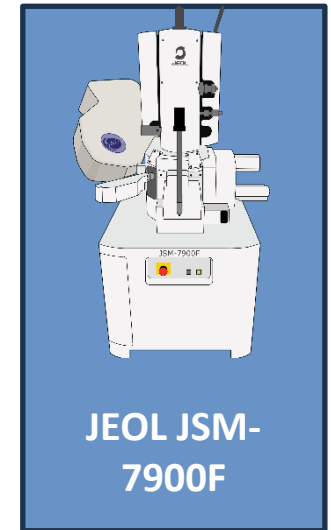
- More signal than energy filtered BSE for most electron energies
- More effective at showing compositional (Z) contrast
- Not as good at very short WD ($< \sim 5$ mm) or very low electron energies ($\sim < 3$ keV)



3. STEM Detectors



Hitachi SU8030



JEOL JSM-7900F

- Powerful nano-particle characterization
- Reflected or transmitted imaging
- Good at very high electron energies (30 keV)

SEM Modes and Techniques

Variable Pressure
Mode (Low Vac)

Beam Deceleration
Mode

X-ray
Microanalysis

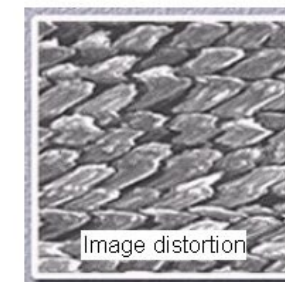
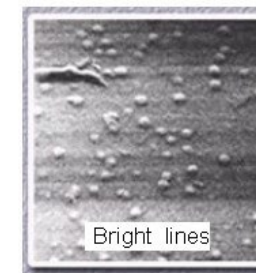
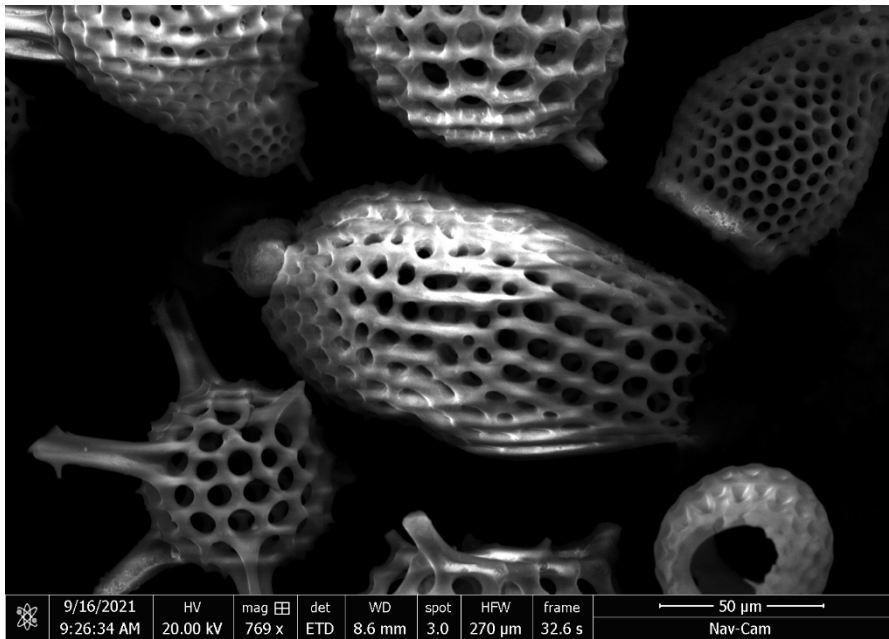
Electron
Backscatter
Diffraction

In-situ Heating and
Cooling

Electron Beam
Lithography (eBL)

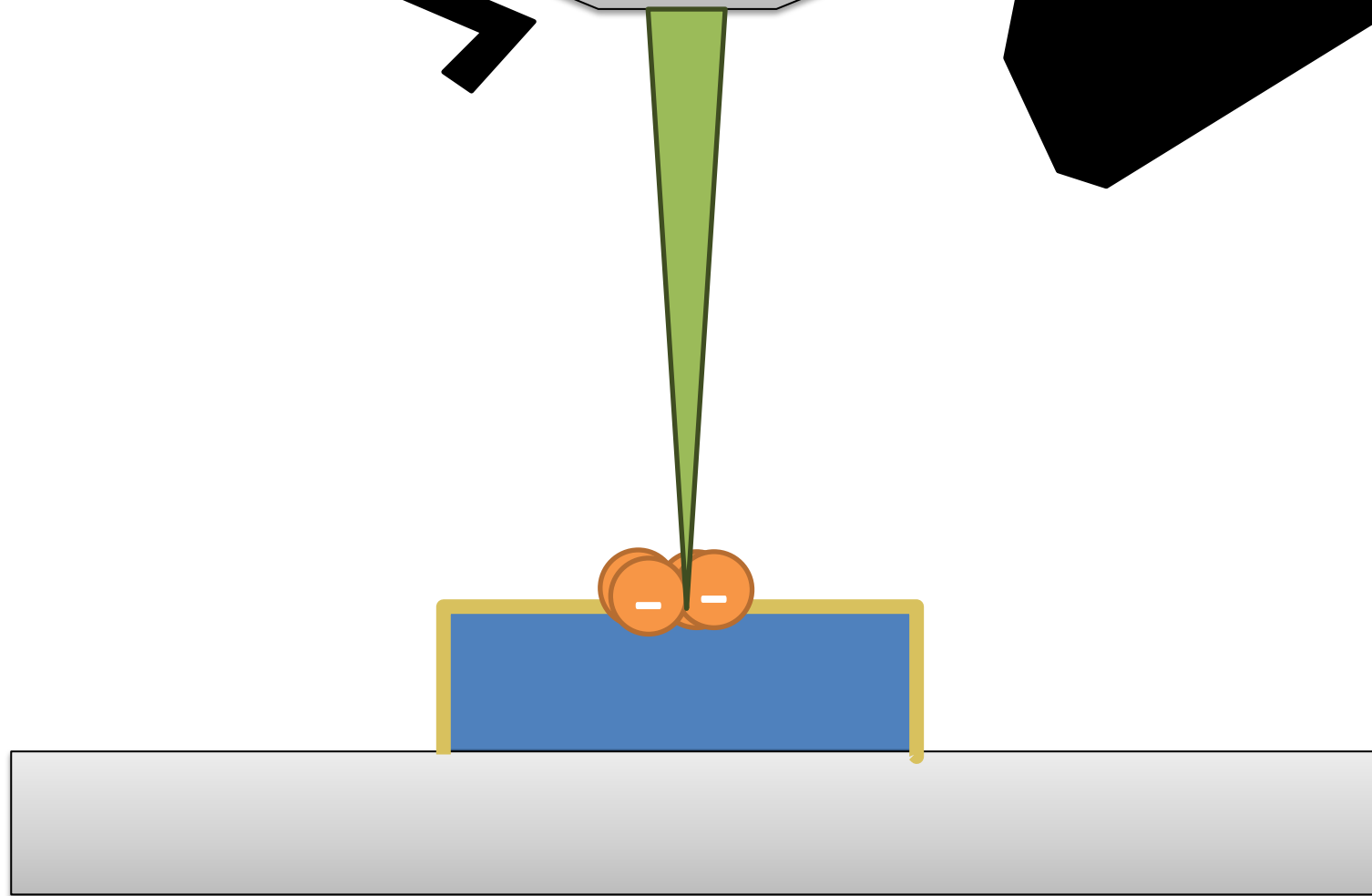
Low-Vacuum Mode

ETD



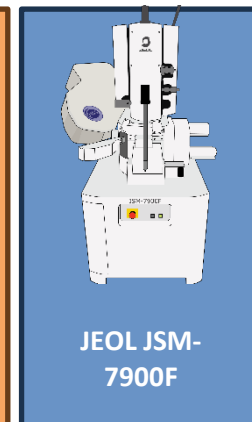
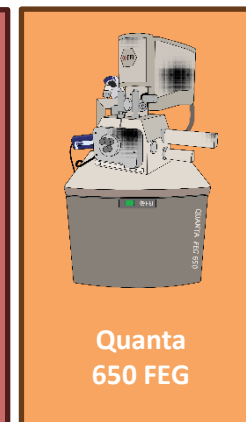
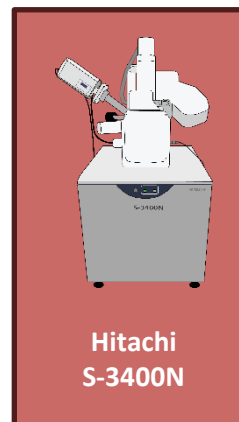
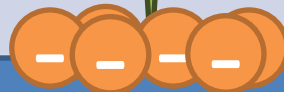
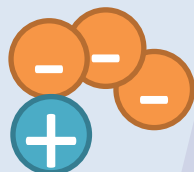
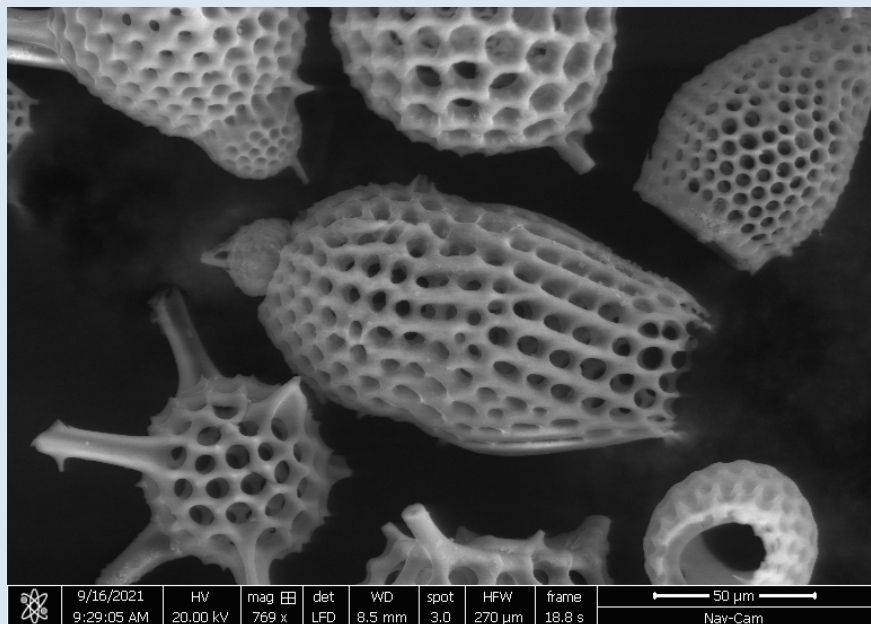
Low-Vacuum Mode

ETD



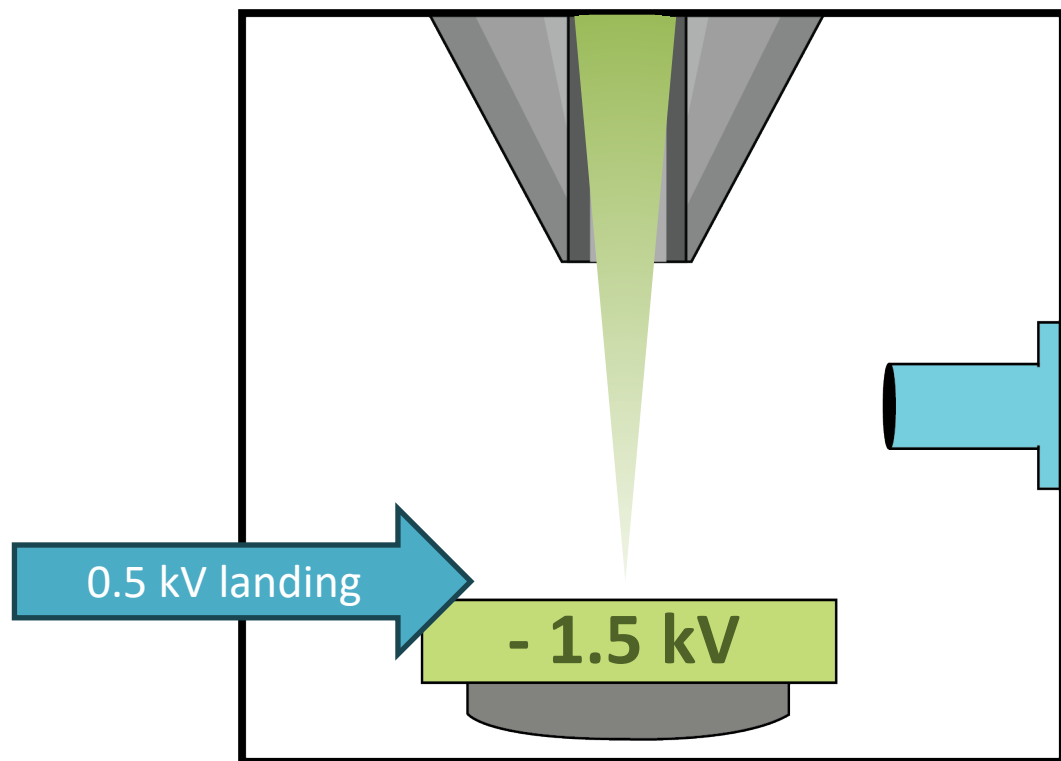
Low-Vacuum Mode

Learn more about heating and Cooling

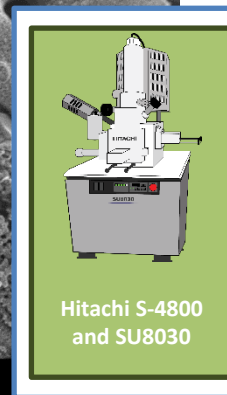
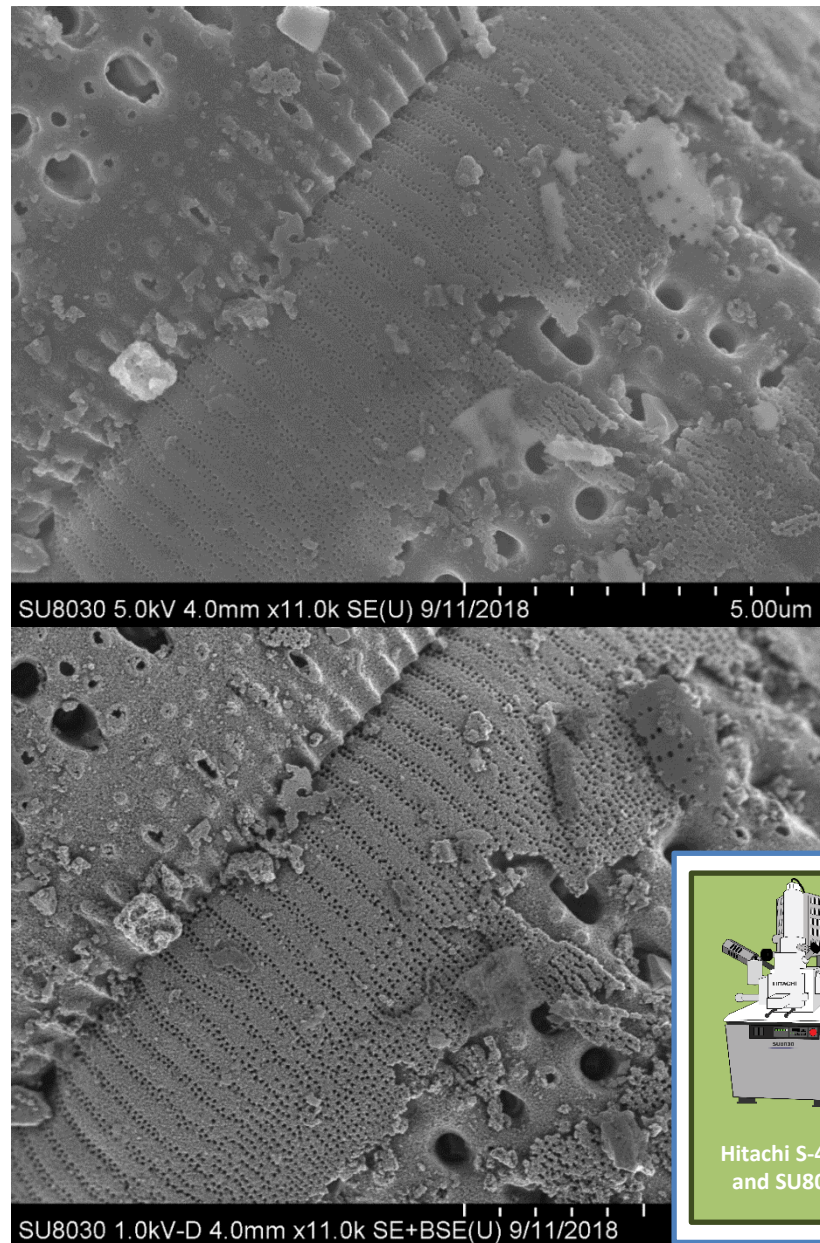


Beam Deceleration

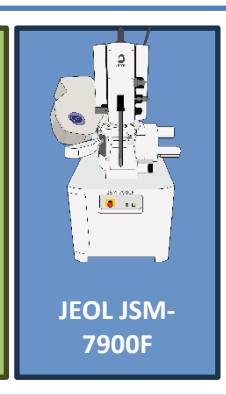
2kV



- Reduces interaction volume while maintaining high resolution imaging
- Reduces affects of lens aberrations on low kV beam

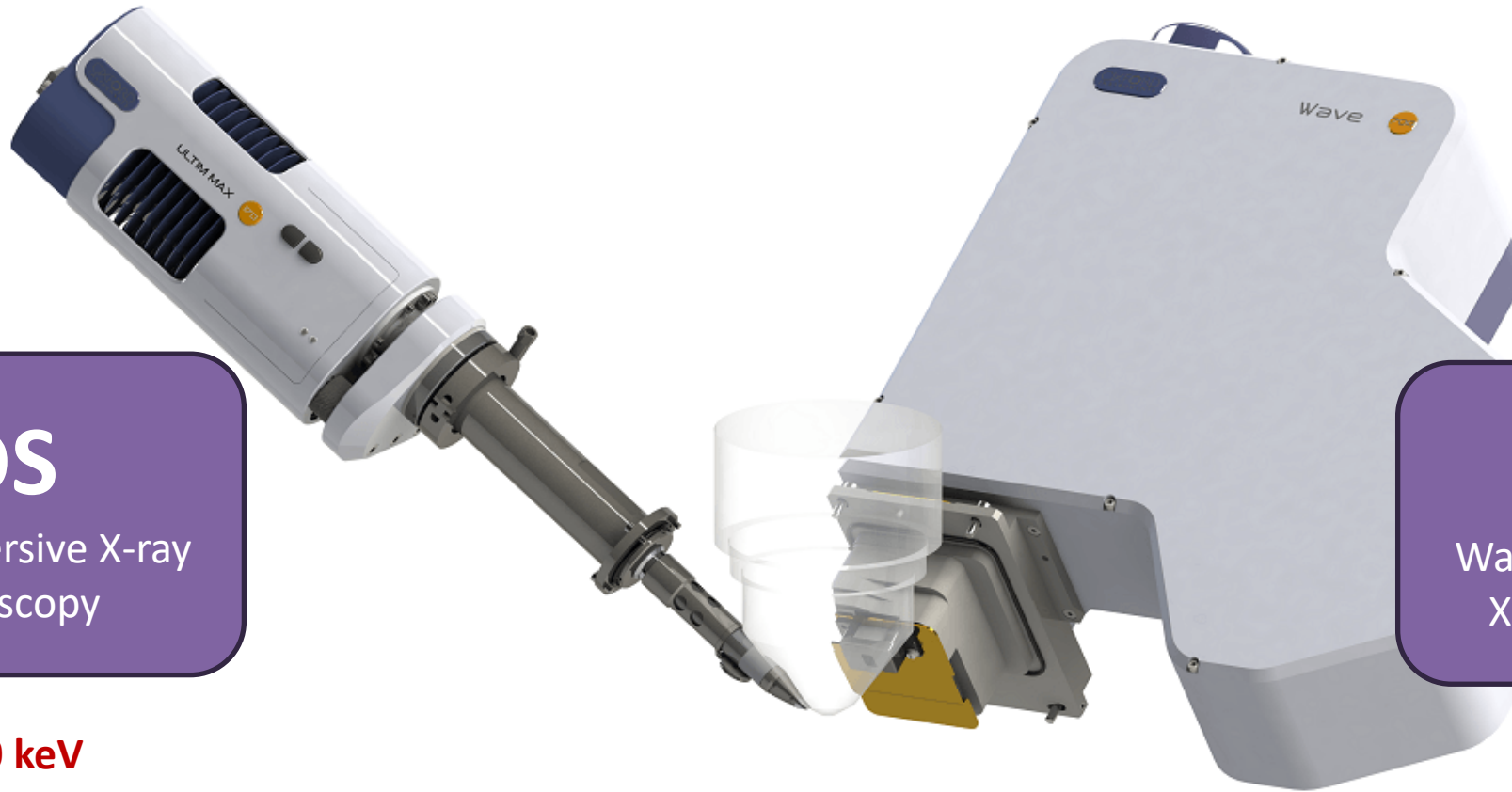


Hitachi S-4800
and SU8030



JEOL JSM-
7900F

X-ray Microanalysis



EDS

Energy Dispersive X-ray Spectroscopy

Si K α = **1.740 keV**
Fe K α = **6.405 keV**

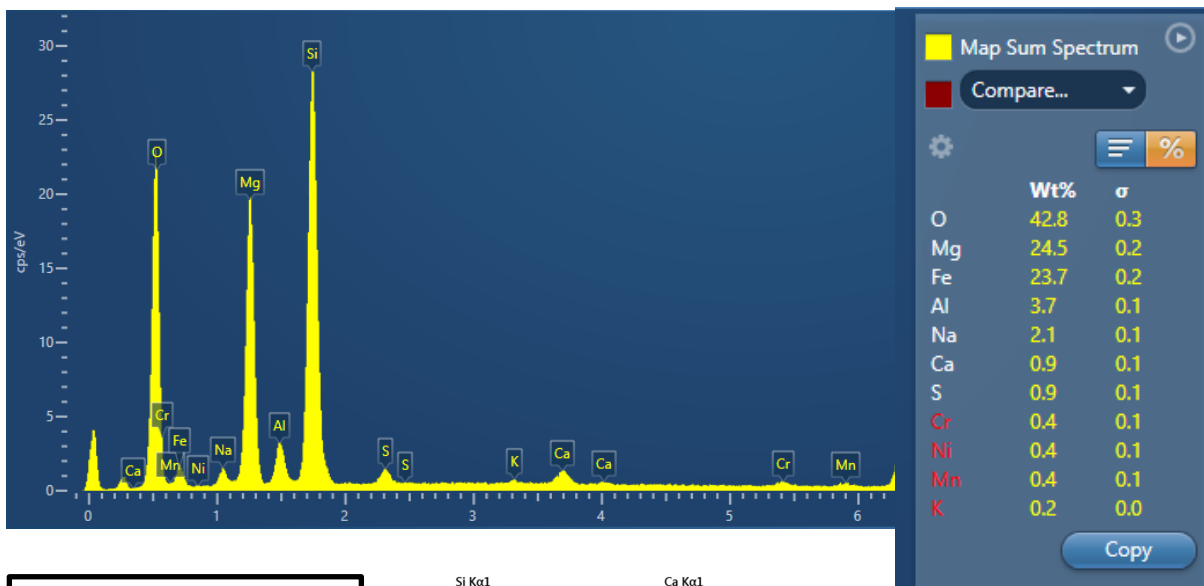
WDS

Wavelength Dispersive X-ray Spectroscopy

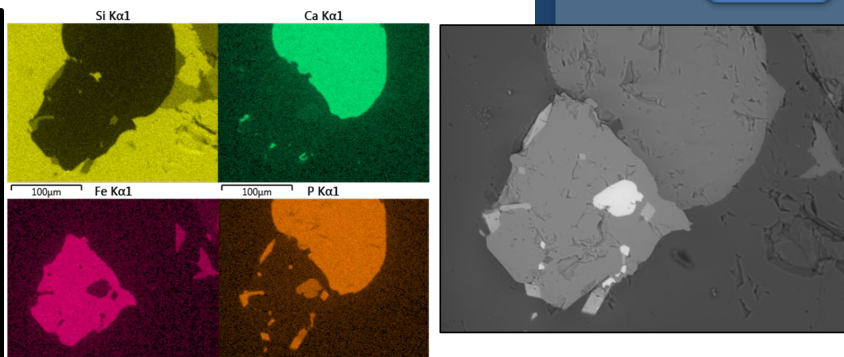
Si K α = **7.13 Å**
Fe K α = **1.94 Å**

EDS

Energy Dispersive X-ray Spectroscopy

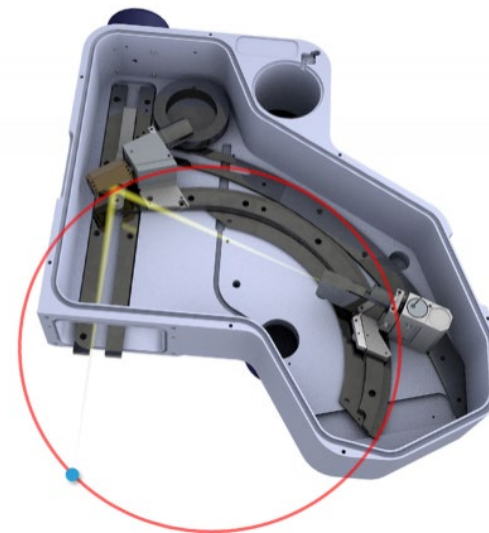
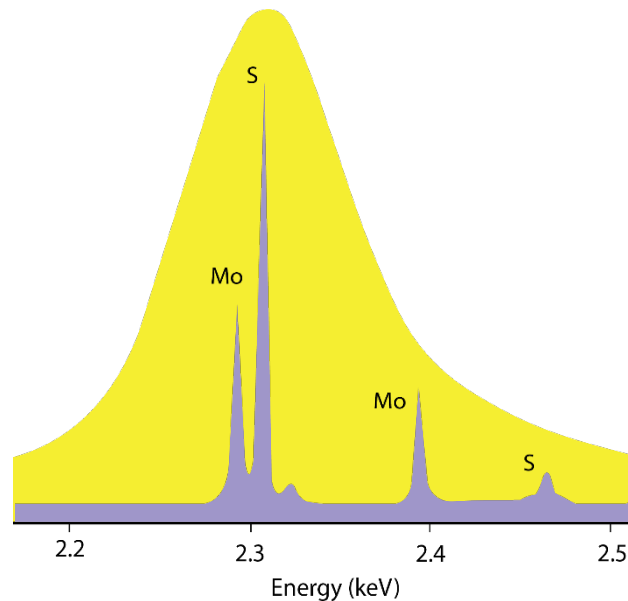


Sign up for EDS Training Demo

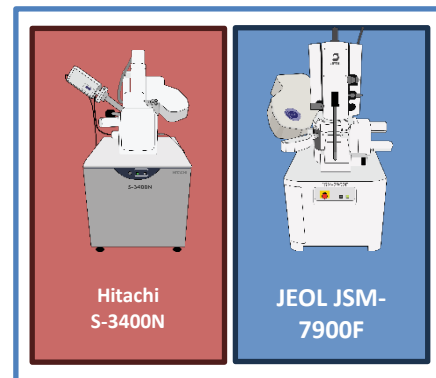


WDS

Wavelength Dispersive X-ray Spectroscopy



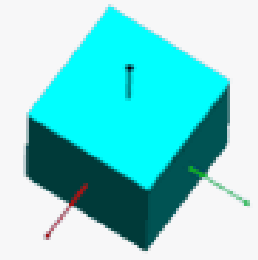
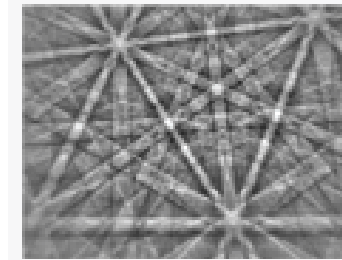
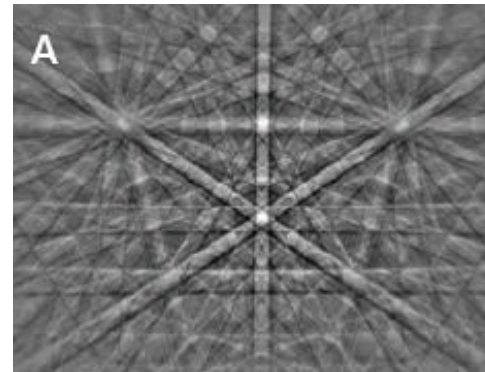
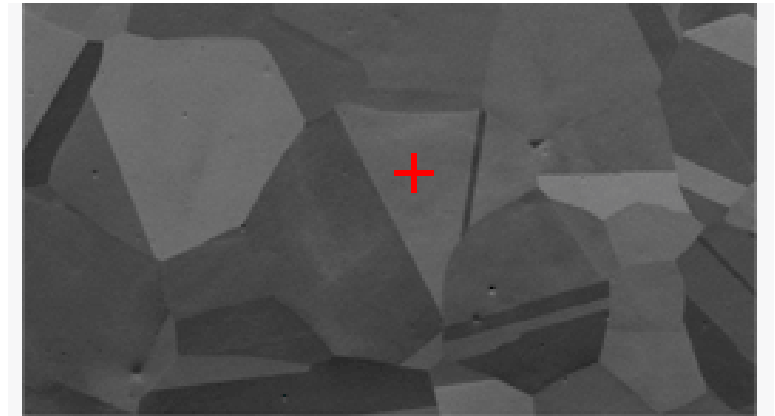
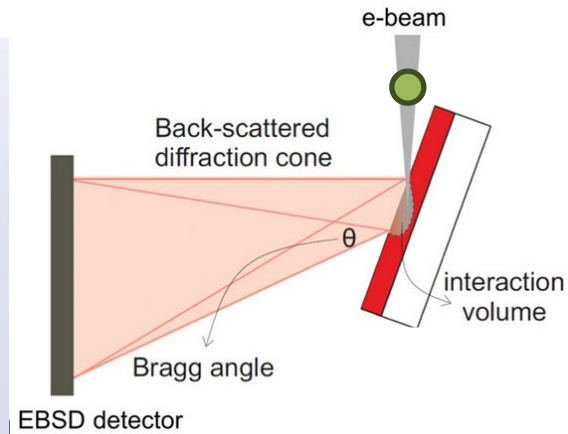
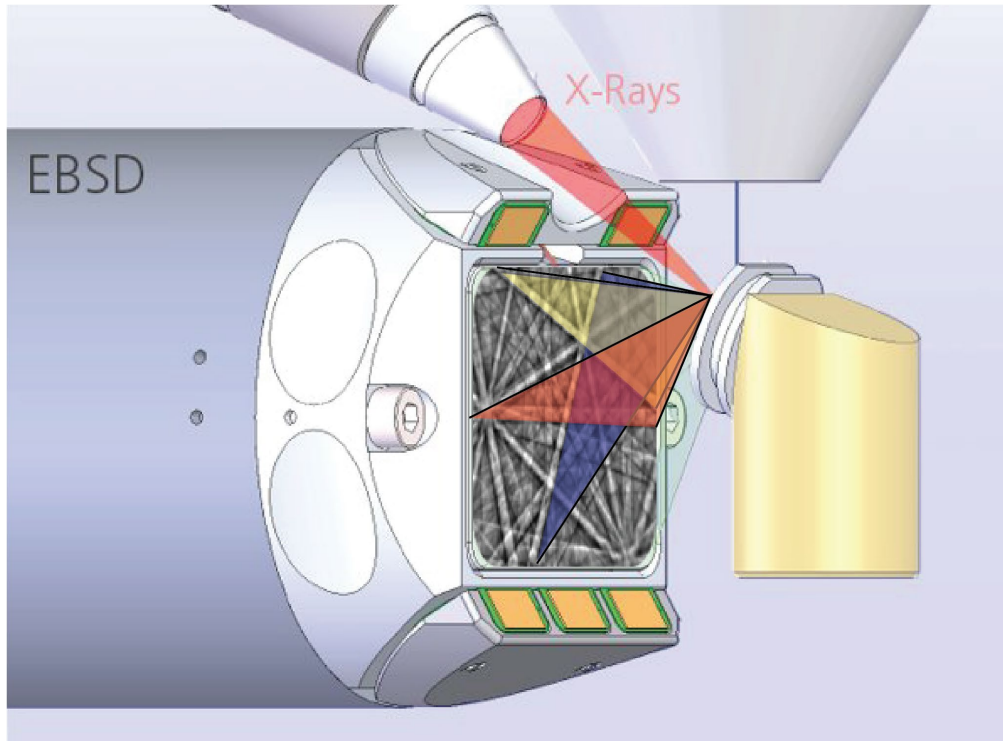
S K α = 2.3 keV
Mo L α = 2.29 keV



Learn more about WDS

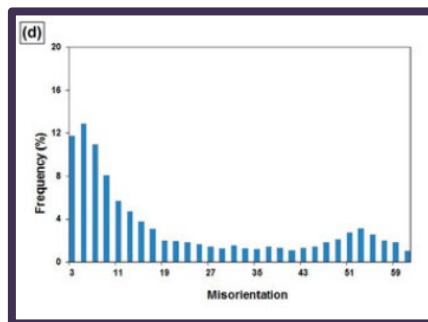
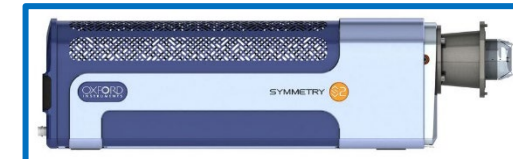
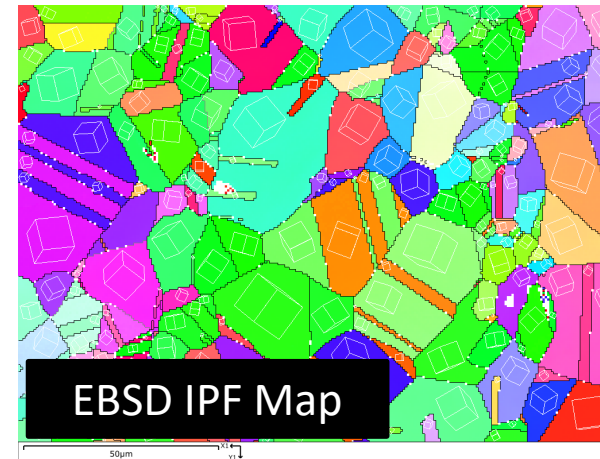


Electron Backscatter Diffraction (EBSD)

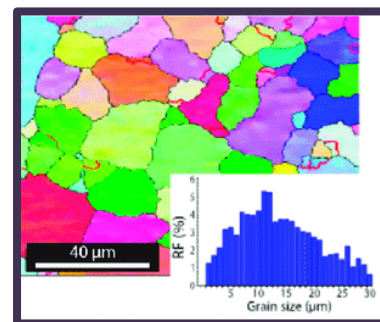


Electron Backscatter Diffraction

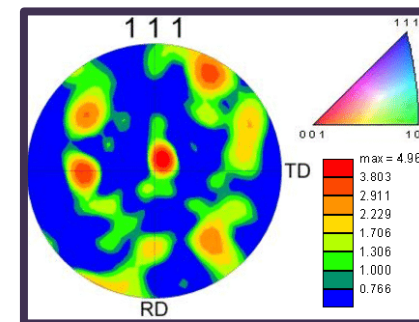
Learn more
about EBSD



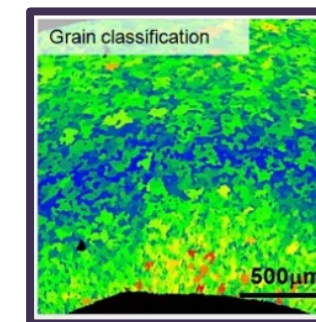
**Boundary
Characteristics**



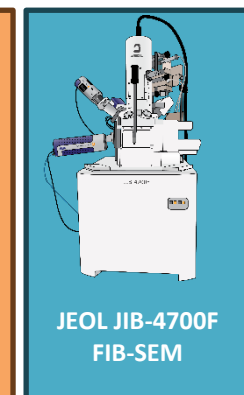
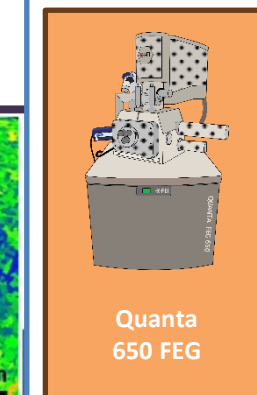
Grain Size



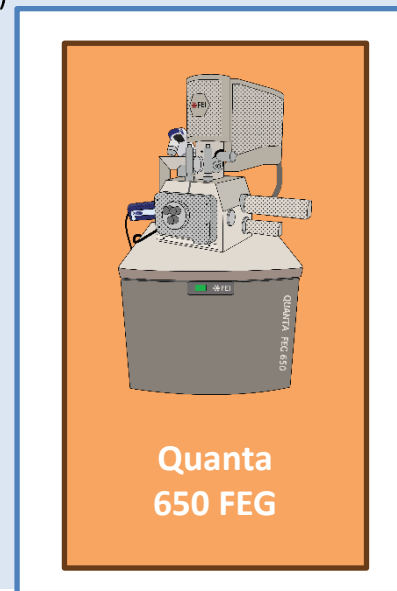
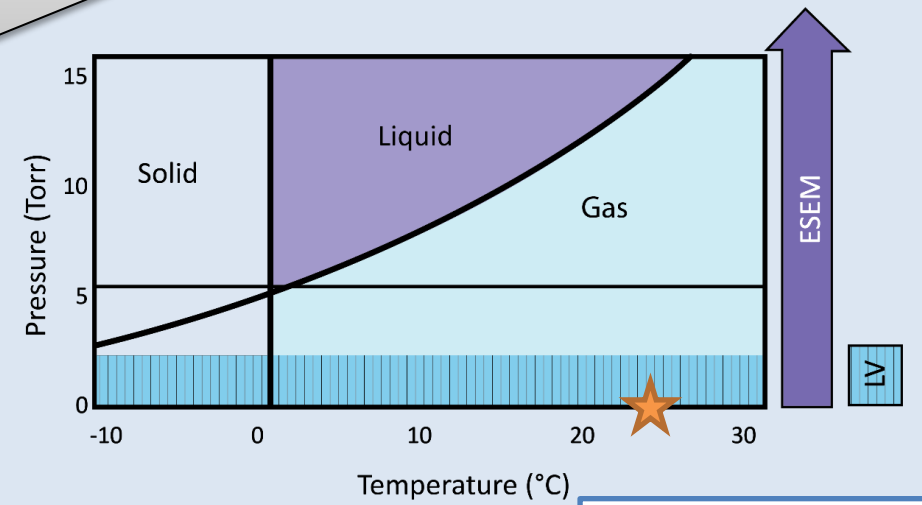
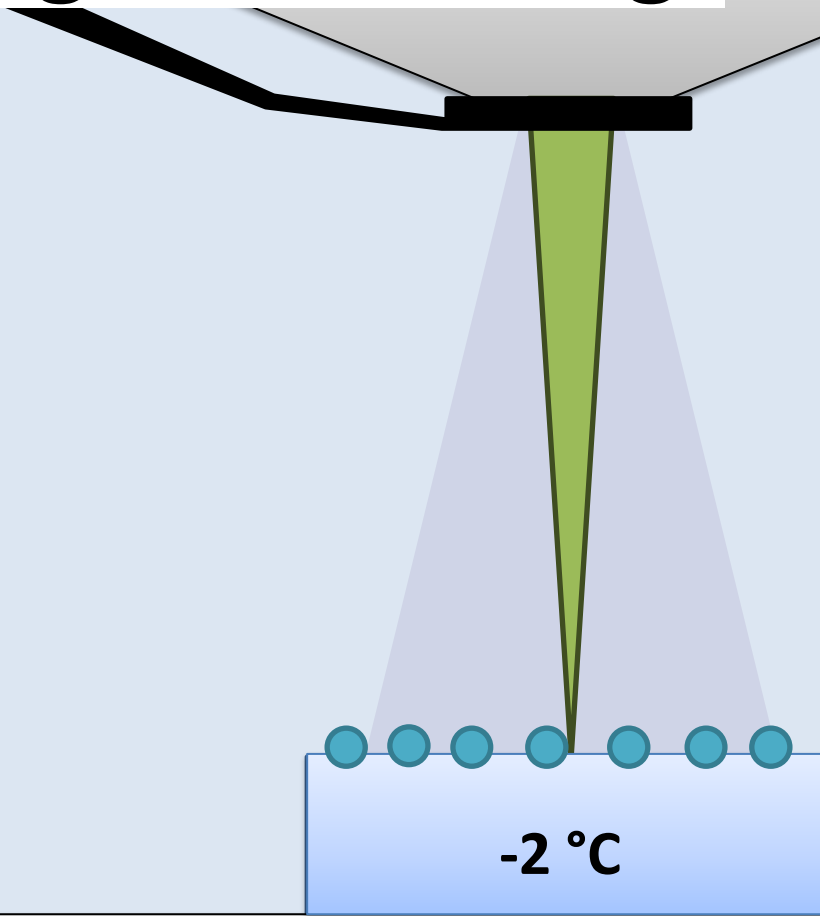
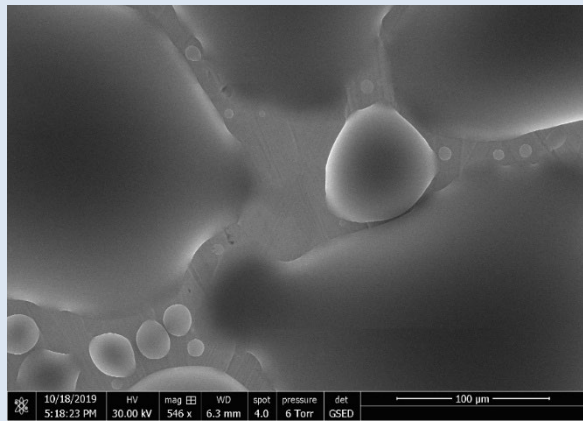
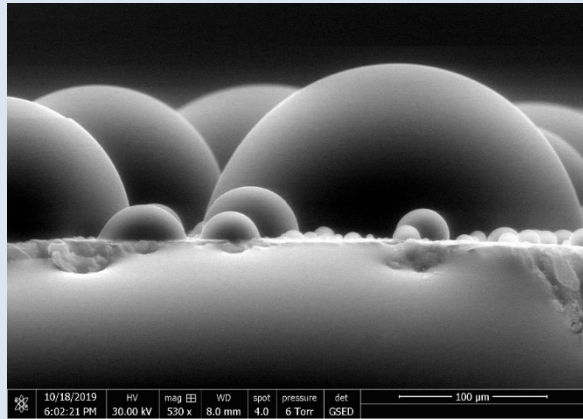
Texture/CPO



Deformation

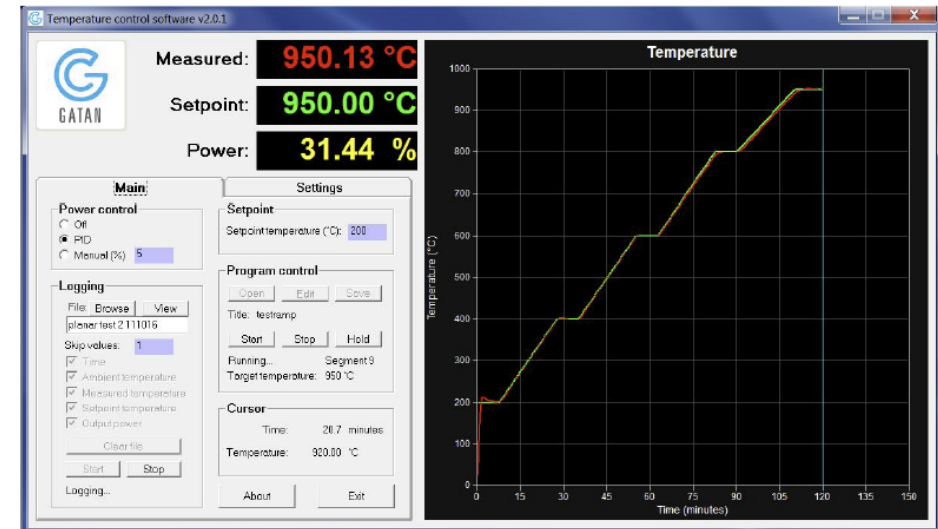
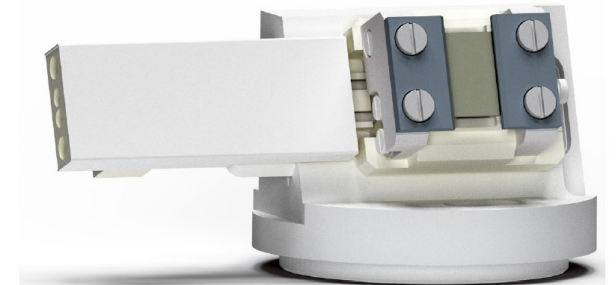
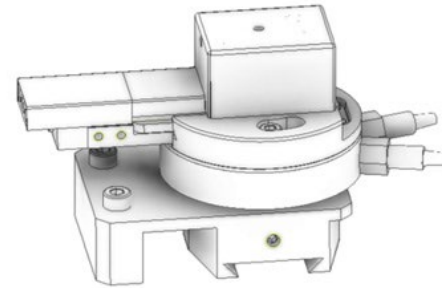


In-situ Heating and Cooling



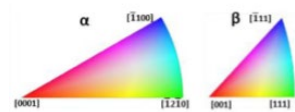
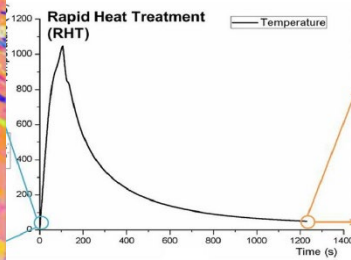
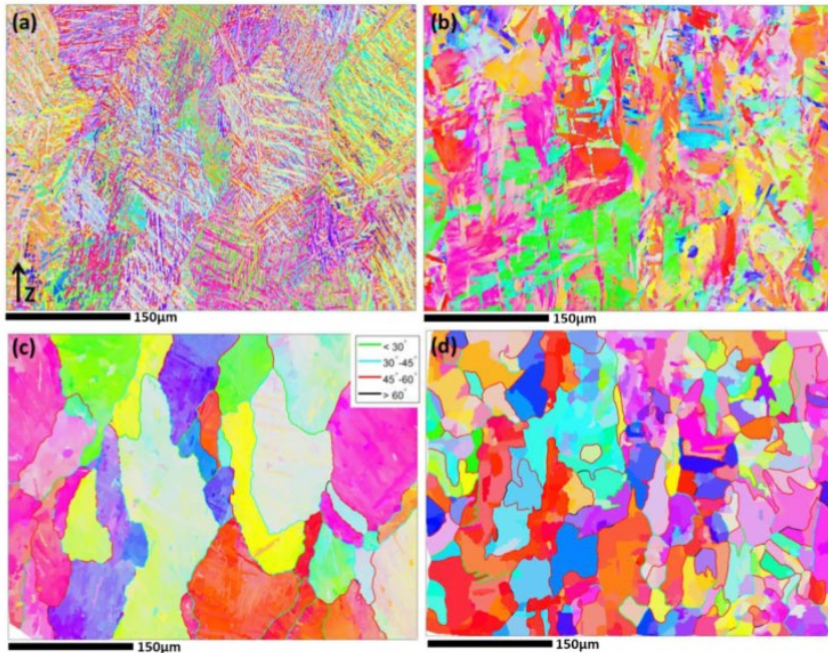
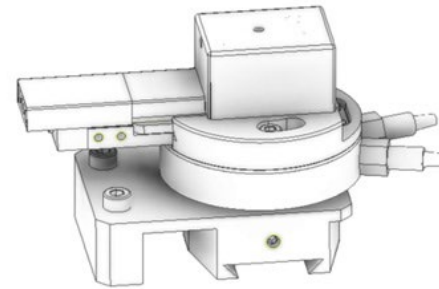
In-situ Heating and Cooling

- Rapid heating and cooling (>100 C/min) of specimens up to several mm in size
- Can heat up to 950 °C
 - Resistance heating
- Excellent temperature control and data logging
- Imaging and EBSD holder

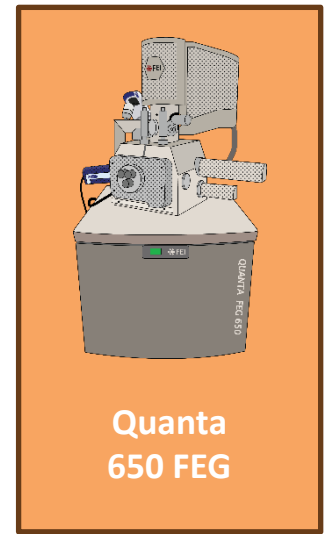
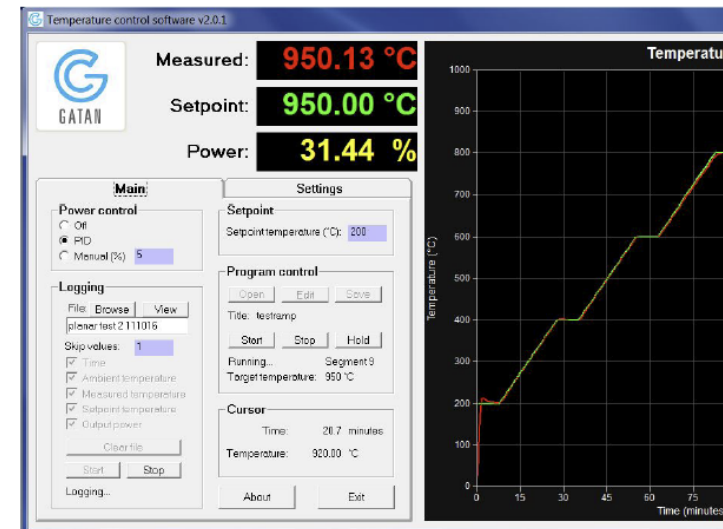


In-situ Heating and Cooling

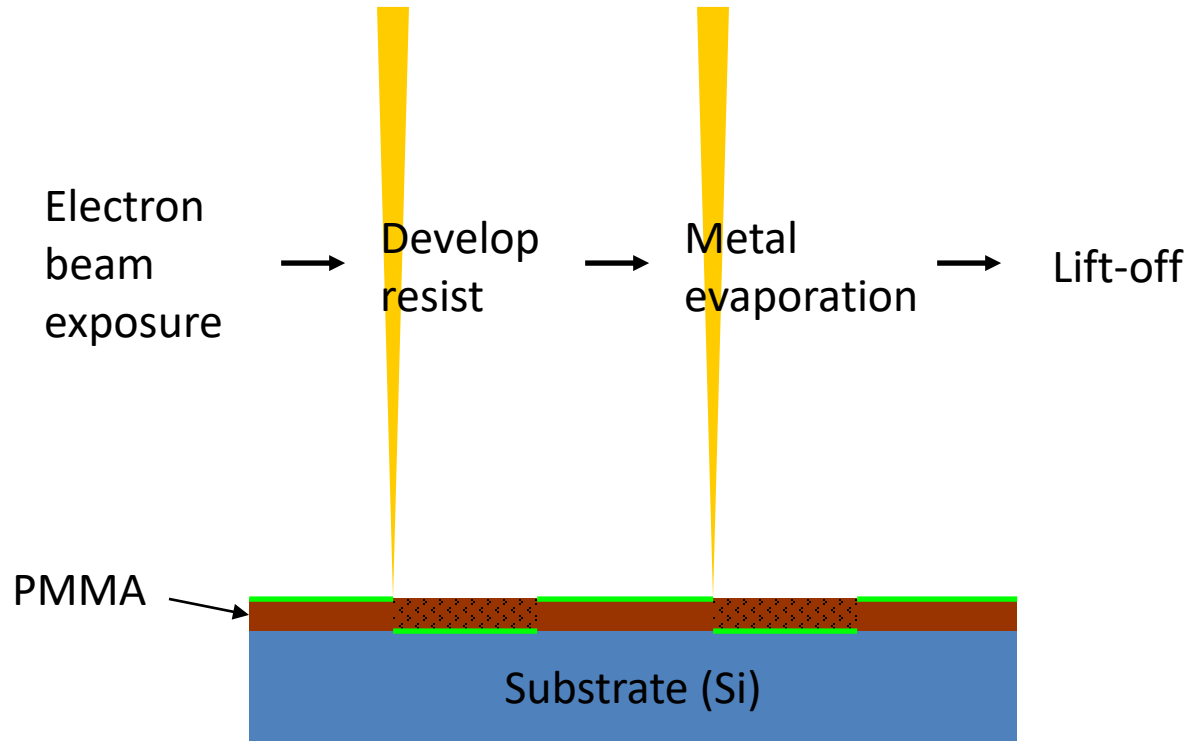
Learn more about heating and Cooling



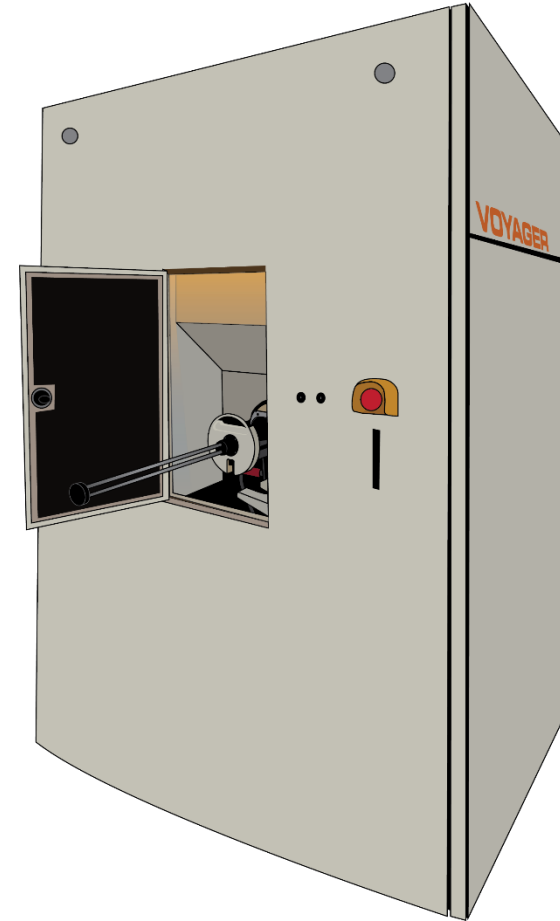
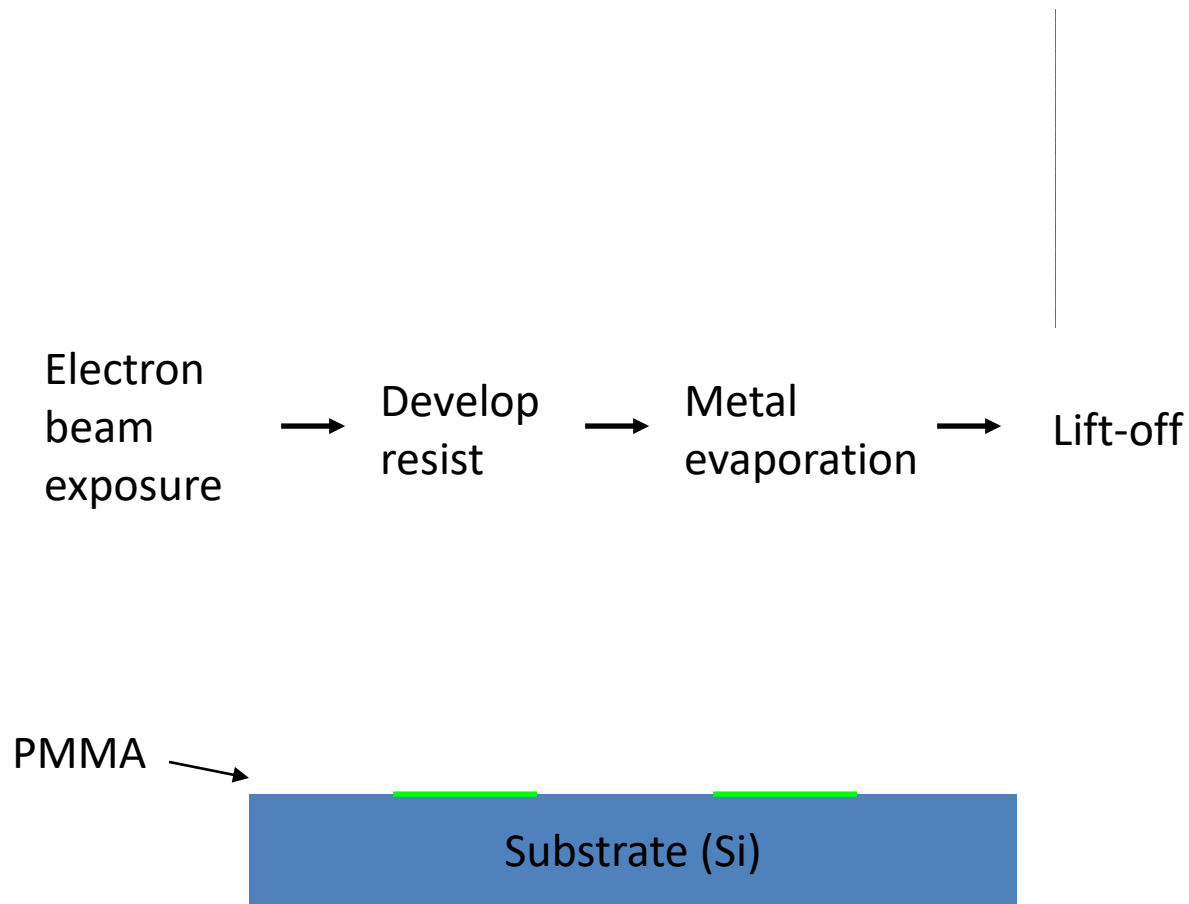
Zou et al., 2020



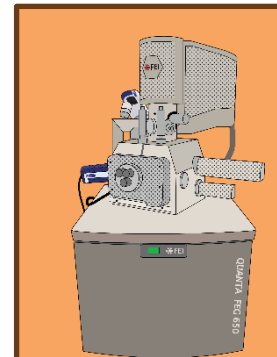
Electron Beam Lithography



Electron Beam Lithography



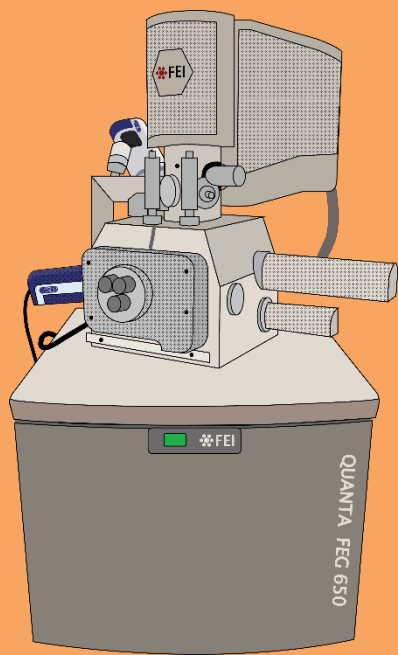
eBL and NUFAB



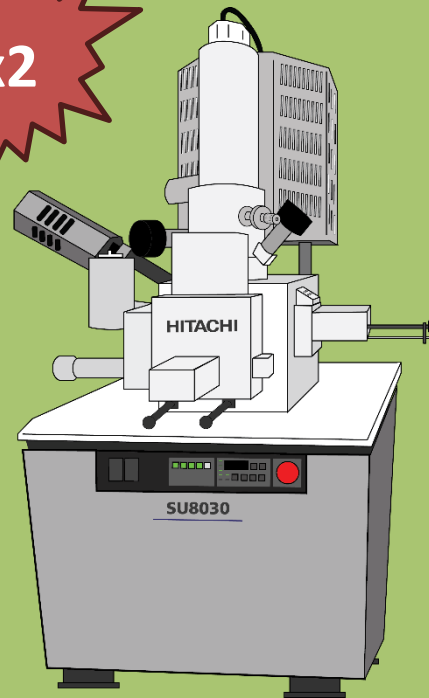
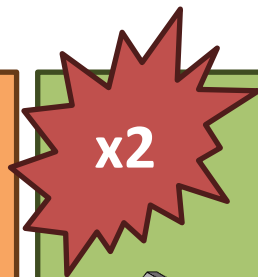
Quanta
650 FEG



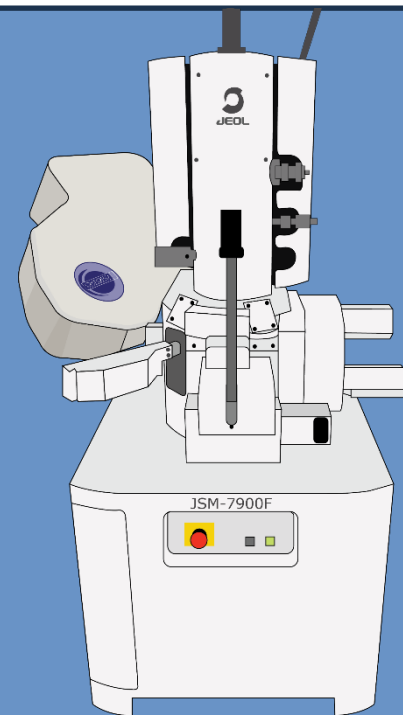
**Hitachi
S-3400N**



**Quanta
650 FEG**



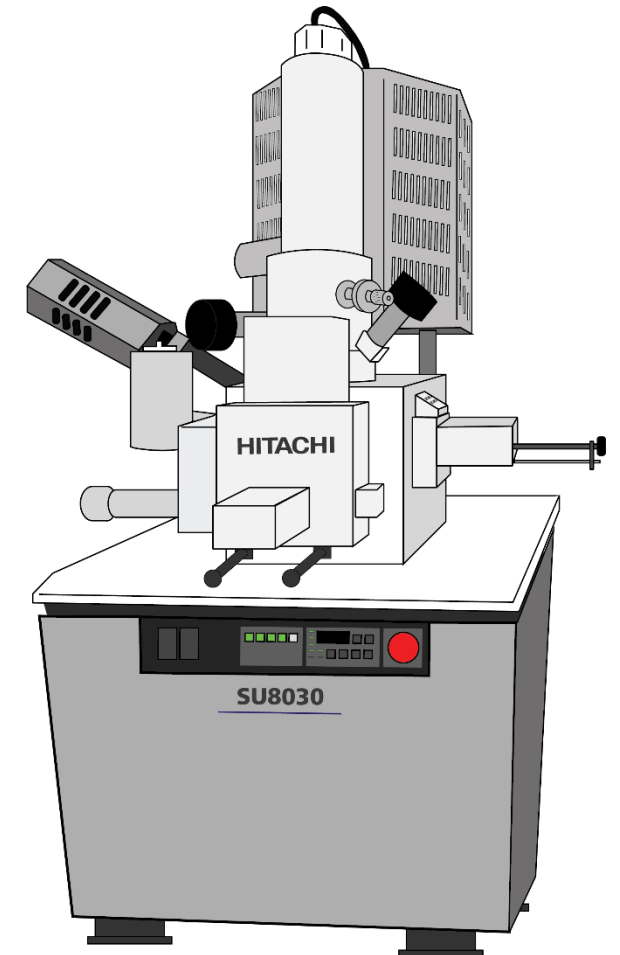
**Hitachi S-4800
and SU8030**



**JEOL JSM-
7900F**

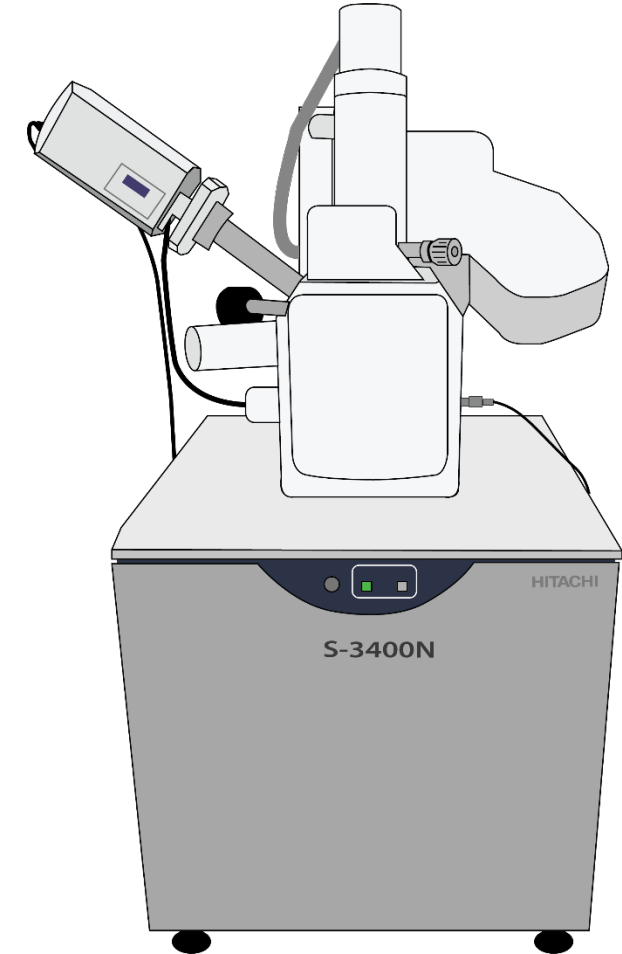
Hitachi S-4800 and SU8030

S-4800	Both	SU8030
<ul style="list-style-type: none"> • 1.5kV beam decel. 	<ul style="list-style-type: none"> • cFEG electron gun 	<ul style="list-style-type: none"> • 2.5kV beam decel.
<ul style="list-style-type: none"> • Oxford INCA SiLi EDS system 	<ul style="list-style-type: none"> • Double condenser optics 	<ul style="list-style-type: none"> • Oxford X-max 80 SDD EDS Detector
<ul style="list-style-type: none"> • Leica Cryo stage with VCT100 transfer system 	<ul style="list-style-type: none"> • In-Lens (upper) SE Detector and ExB filter 	<ul style="list-style-type: none"> • Additional Top (upper) SE Detector
	<ul style="list-style-type: none"> • SE Detector (lower) 	<ul style="list-style-type: none"> • Low kV STEM Detector
	<ul style="list-style-type: none"> • Compucentric stage 	
	<ul style="list-style-type: none"> • Vibration isolation table 	



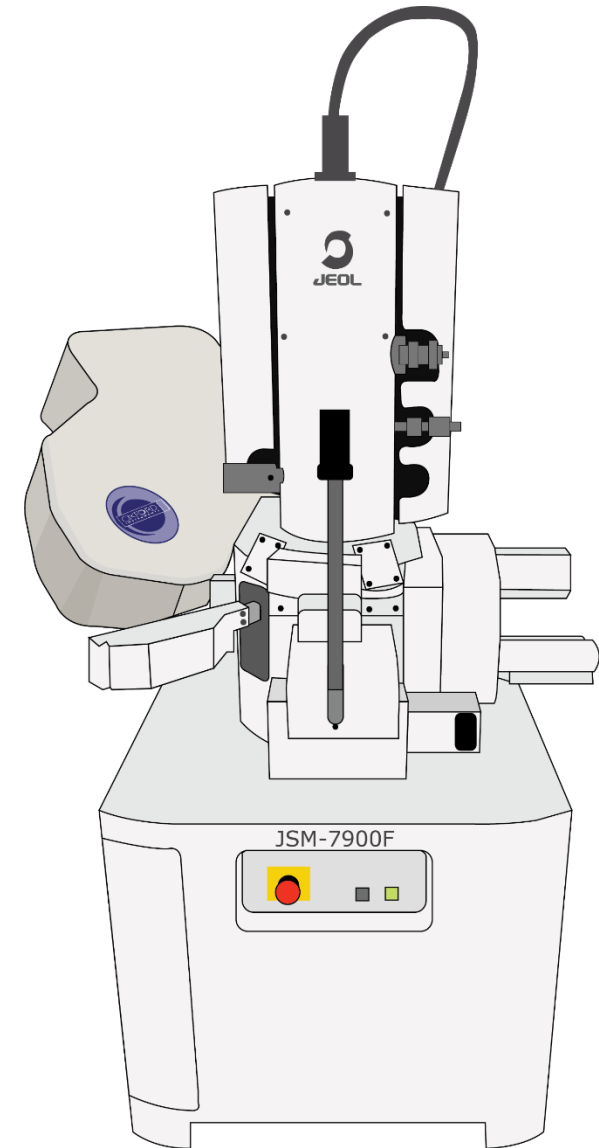
Hitachi S-3400

- Tungsten filament electron gun
- Large specimen chamber (up to 8" diameter, 85 mm tall specimens)
- Compucentric stage
- ESED II Detector for low vacuum imaging
- 5 segment solid state BSE Detector with 3D reconstruction capability
- Oxford INCAx-act SDD EDS
- Oxford WAVE 500 WDS system



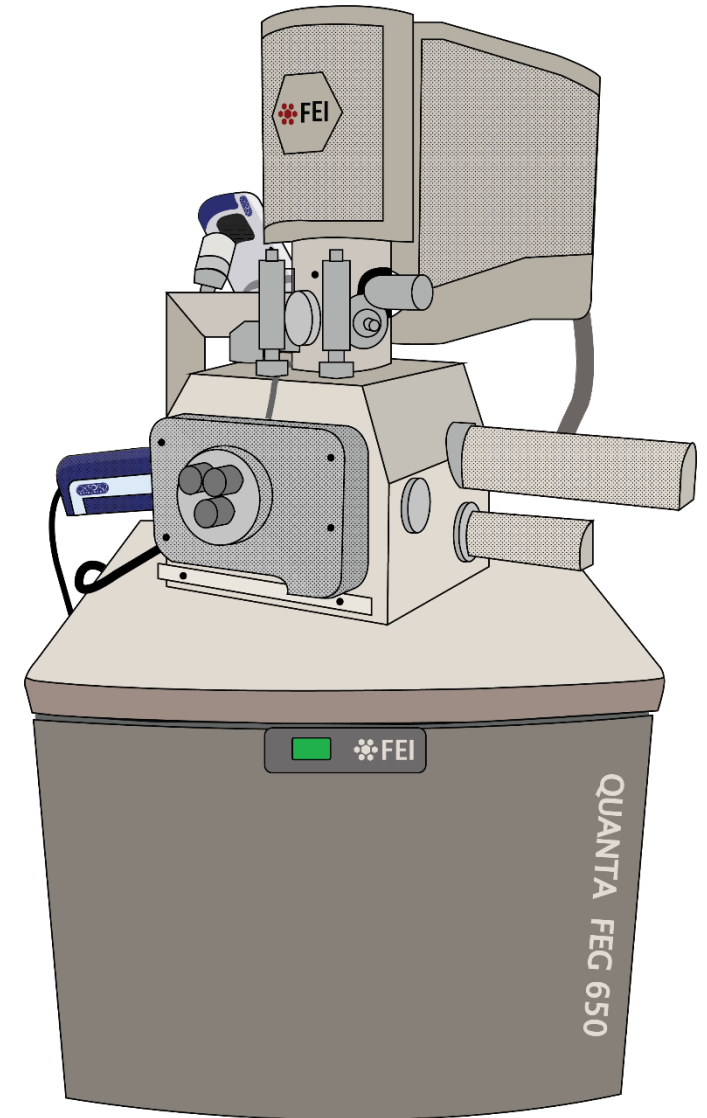
JEOL JSM-7900F

- Schottky Plus field emission gun with low aberration condenser lens
- Ultralow kV in-lens (upper) detectors
- GENTLEBEAM™ Super High mode, up to 5kV beam decel.
- Super Hybrid (electrostatic) Lens (SHL) enabling magnetic material analysis
- High sensitivity retractable BSE detector
- Oxford Ultimax 65 SDD EDS Detector
- Oxford WAVE 700 WDS system
- Low vacuum mode
- Low kV STEM imaging

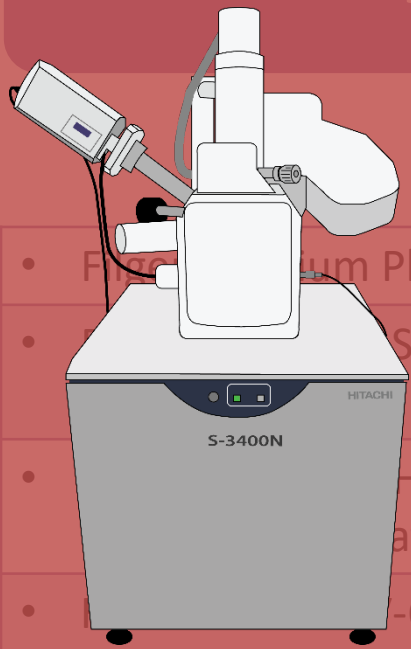


Quanta 650F

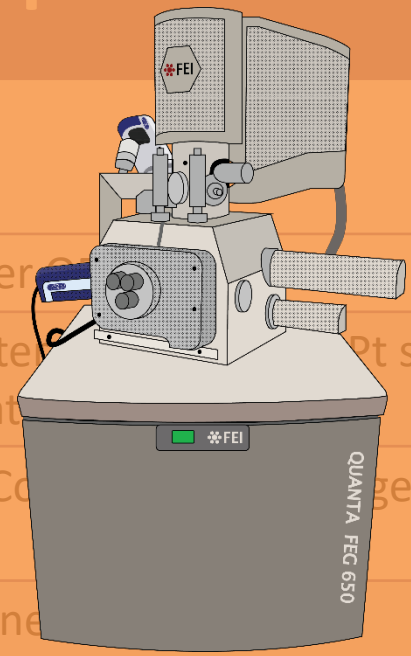
- Schottky field emission gun
- Standard SE (lower), SS concentric BSE (retractable), 2 gaseous SE, and gaseous BSE Detectors
- Large chamber and programmable stage with 6" wafer capacity
- Low vacuum mode up to 4000 Pa chamber pressure
- Oxford SDD EDS and EBSD system
- eBL setup including beam blanker, NPGS software, and integrated beam current measurement system
- Gatan Murano heating/cooling stage



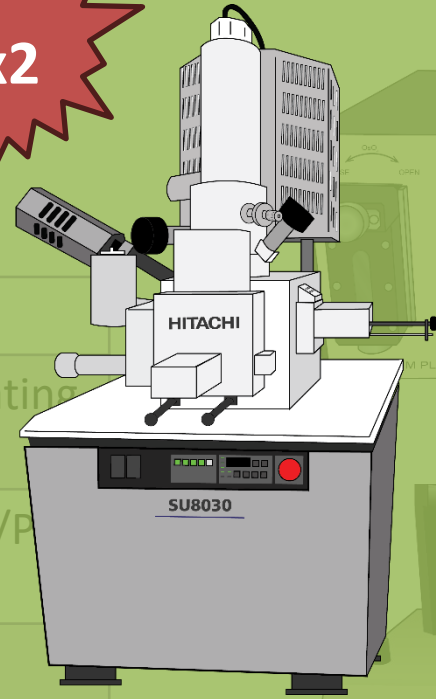
Sample Preparation



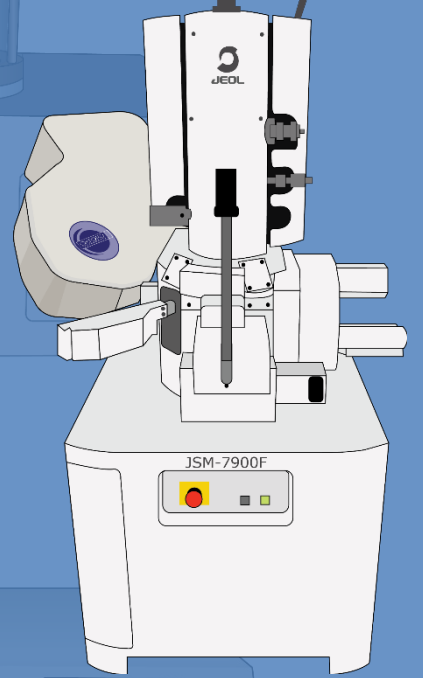
**Hitachi
S-3400N**



**Quanta
650 FEG**



**Hitachi S-4800
and SU8030**



**JEOL JSM-
7900F**

Thank you!



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